



June 4, 2019

## Leti Photonics & MicroLED Displays Workshop

NTUH International Convention Center, Taipei, Taiwan

# CHALLENGES AND SOLUTIONS FOR ADVANCED MICROLED DISPLAYS

Challenges and solutions for advanced microLED displays

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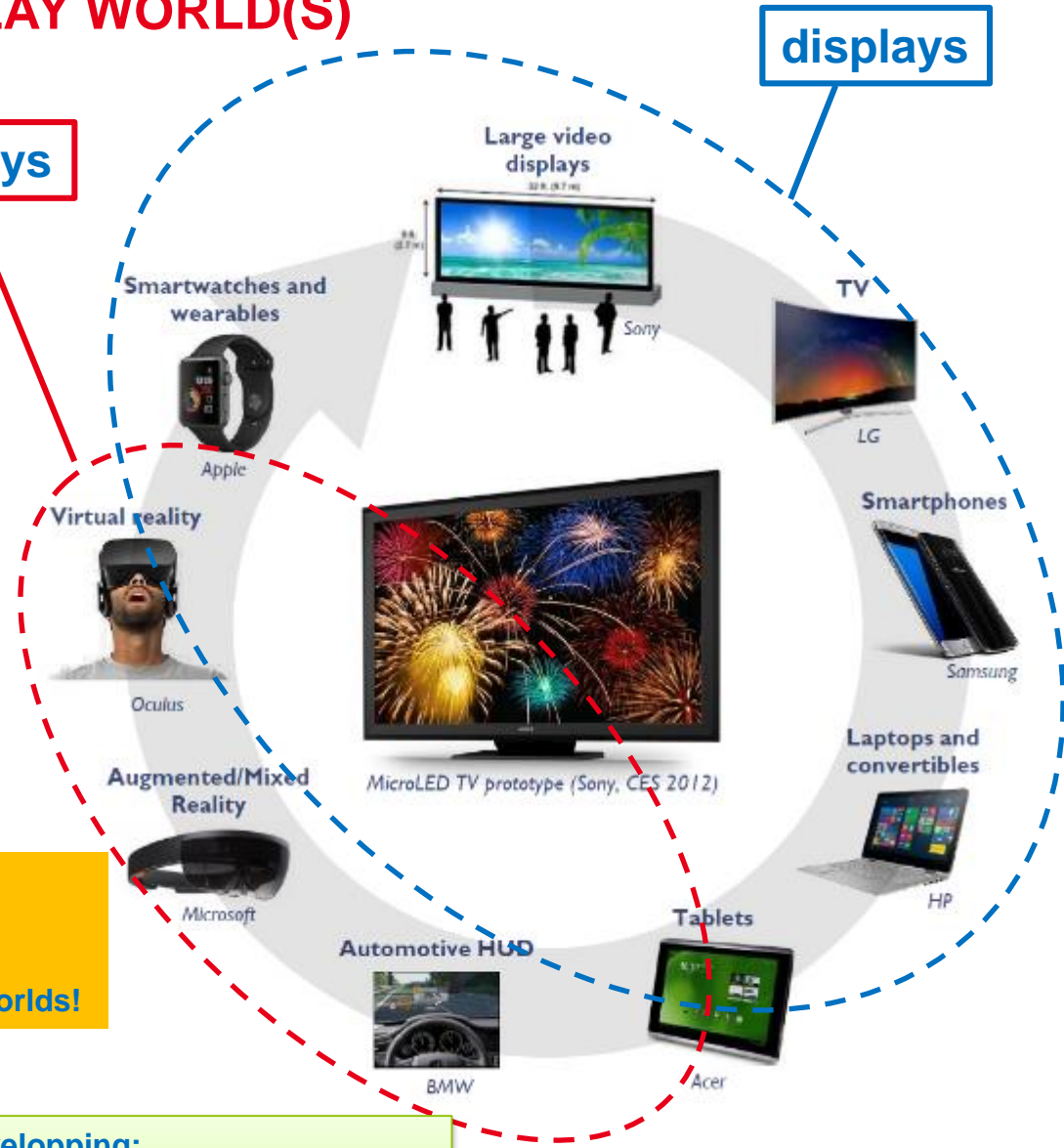
# CONTEXT: THE DISPLAY WORLD(S)

TODAY, the display worlds:

- **Microdisplays:**
  - LCD, OLED, MEMS, ..
  - CMOS technology
- **Displays:**
  - LCD, OLED, ...
  - TFT technology

**microdisplays**

**displays**



**microLED technology:**

- now emerging
- TOMORROW:
  - Will bring revolution in both displays worlds!

**LETI intends to participate to this revolution by developing:**

- Ultrahigh-brightness LED microdisplays for Augmented Reality applications
- Advanced solutions for large area microLED displays

- ❑ Introduction
- ❑ Challenges and (some) solutions for GaN microdisplays
  - ❑ LED microdisplays fabricated with hybridization technology
    - ❑ Gen1 and Gen2 GaN microdisplay demonstrators
  - ❑ LED microdisplays fabricated with direct bonding technology
  - ❑ Other challenges for microdisplays
- ❑ Challenges and (some) solutions for MicroLED displays
  - ❑ microLED Transfer process
  - ❑ microLED display driving
- ❑ Conclusion

# INTRODUCTION: WHY GaN MICRODISPLAYS?

Head-mounted Displays  
→ see-through systems



Augmented reality

See more, hands-free.



New applications /  
New markets

New requirements:

- system
- display

System requirement:

- Compactness
- Field of view (immersion)

OLED microdisplay

emissive



1000 Cd/m<sup>2</sup>

Need more..

Microdisplay requirement:

- Image quality
- Compactness
- Low consumption
- High brightness

New display: iLED GaN  
microdisplay

# ILED: GAN EMISSIVE MICRODISPLAYS



GaN for LED lighting  
Brightness, efficiency,...

GaN for LED displays

→high brightness  
→Reliability: LT, T°

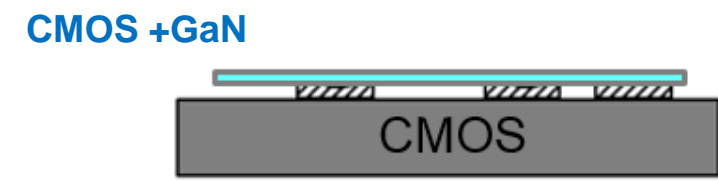
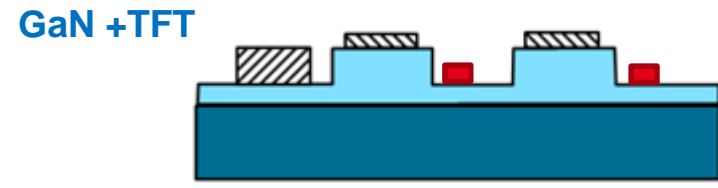
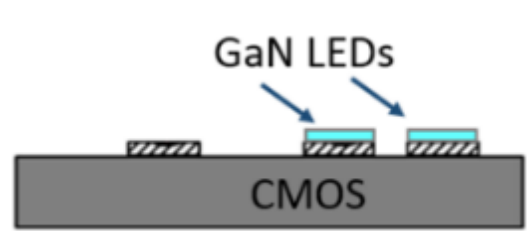
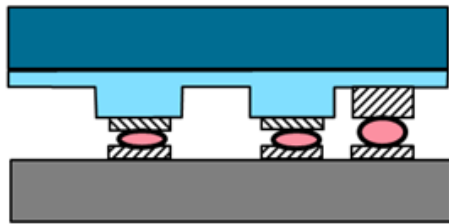
Existing approaches for GaN displays fabrication:

GaN array + active matrix?

GaN: High T°

Hybridization / 3D integration:

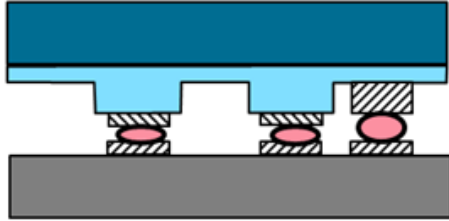
Monolithic:



- LETI:
- Hybridization
  - Monolithic CMOS+ GaN

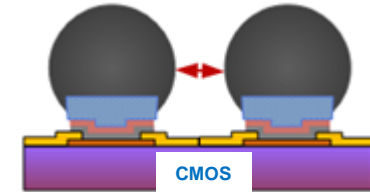
## CHALLENGES FOR HYBRIDIZATION OF MICRODISPLAYS

### Hybridization?



Classical hybridization technique:  
flip-chip In bump

Pitch limitation: 15  $\mu\text{m}$

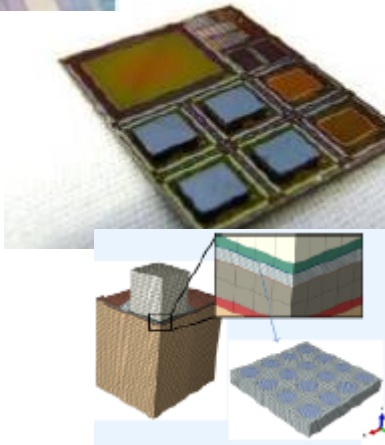
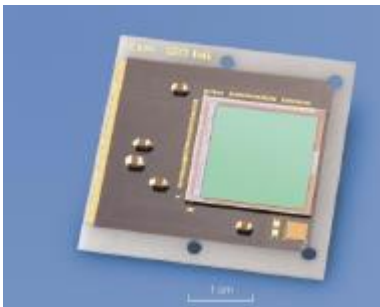


Case of microdisplays:

- 10  $\mu\text{m}$ , towards 5  $\mu\text{m}$
- GaN: CTE mismatch compatible

→ *Other solution needed*

### Hybridization technologies at LETI: 3D, image sensors, ...



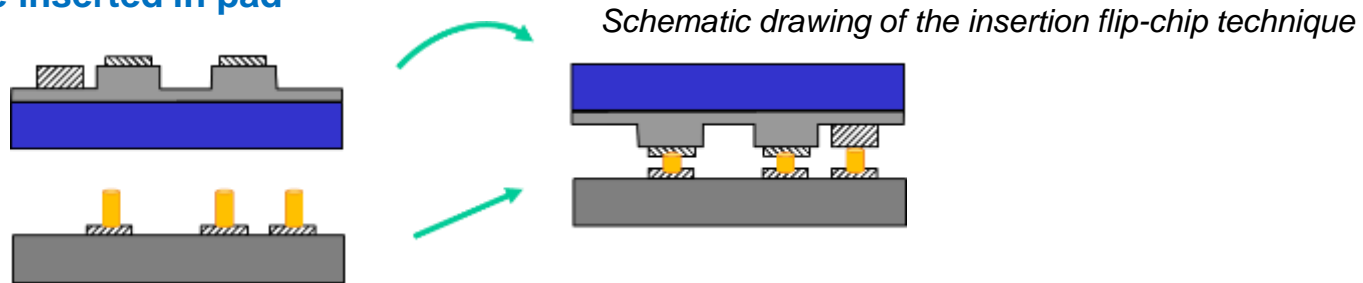
Many hybridization technologies

### Microtube technology

# LED MICRODISPLAYS FABRICATED WITH HYBRIDIZATION TECHNOLOGY

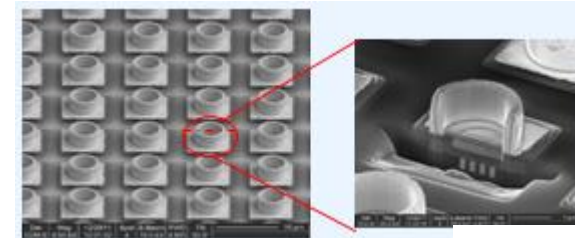
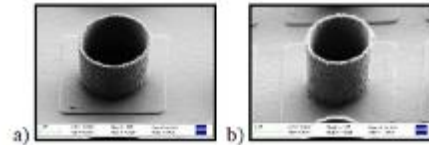
## Hybridization with micro-tube technology

Principle:  $\mu$ Tube inserted in pad



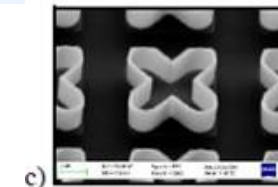
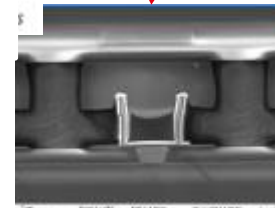
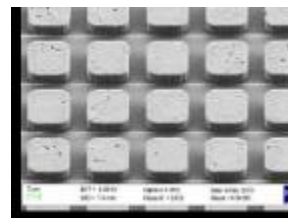
Microtubes on silicon side:

silicon side: ROC, active-matrix



Pads on opposite side:

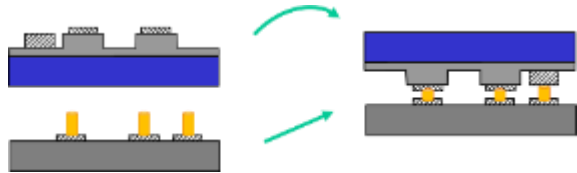
top side: sensor, ...GaN array



- Room temperature assembly using thermo-compression
- Few mN per connection
- Multi materials approach possible for insertion
- Standard IC technology

# DISPLAY DEMONSTRATORS

2 types of display demonstrators



Demo Gen 1

Demo Gen 2

GaN Array

10  $\mu\text{m}$  pitch

10  $\mu\text{m}$  pitch

Resolution

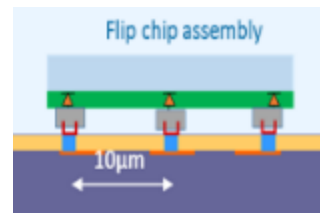
300 x 252

873 x 500 (WVGA)

Driving circuit

1-level connection  
Silicon circuit

Full CMOS active-matrix



Objective

- Demonstrate
- 10  $\mu\text{m}$  pixel pitch
  - GaN potential (Power)

- Demonstrate
- High res; small pitch (10  $\mu\text{m}$ )
  - Full video operation

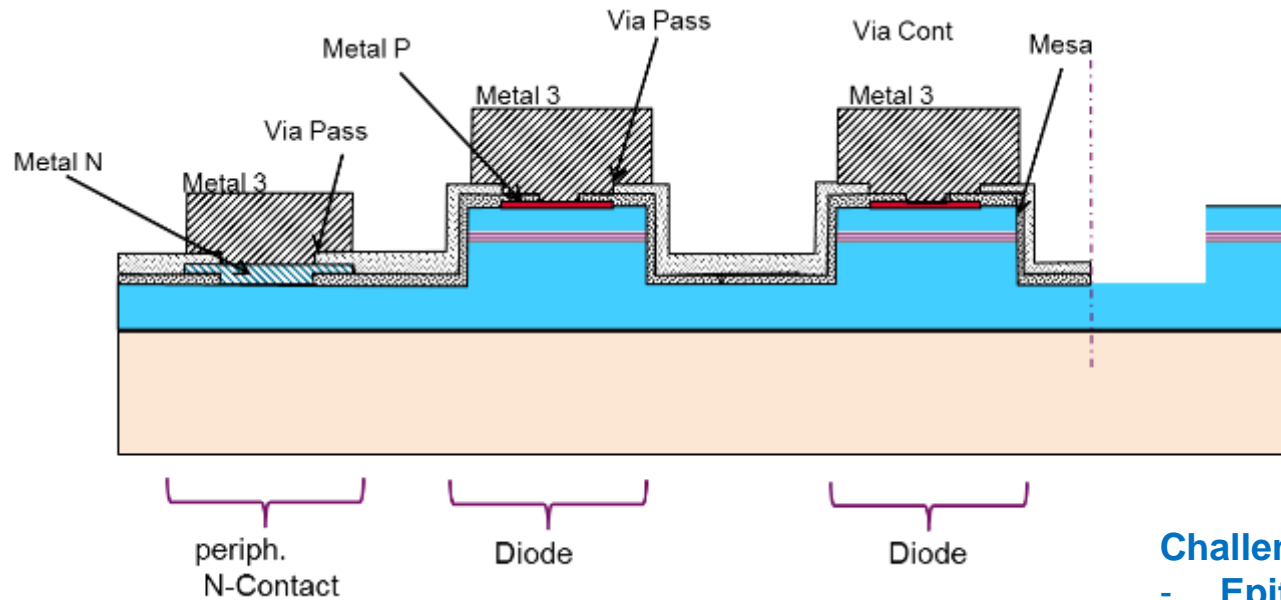
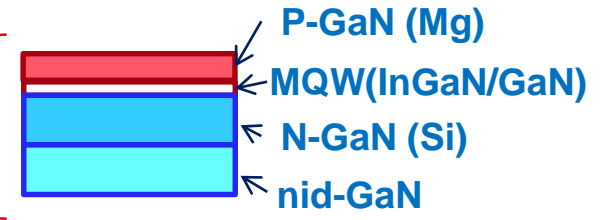


# DEVELOPMENT OF 10 μM PITCH GAN LED ARRAY

## GaN Diode process on sapphire

- Towards small-pitch LED arrays
- Development of dedicated process

Epi LED structure:  
(MOCVD)



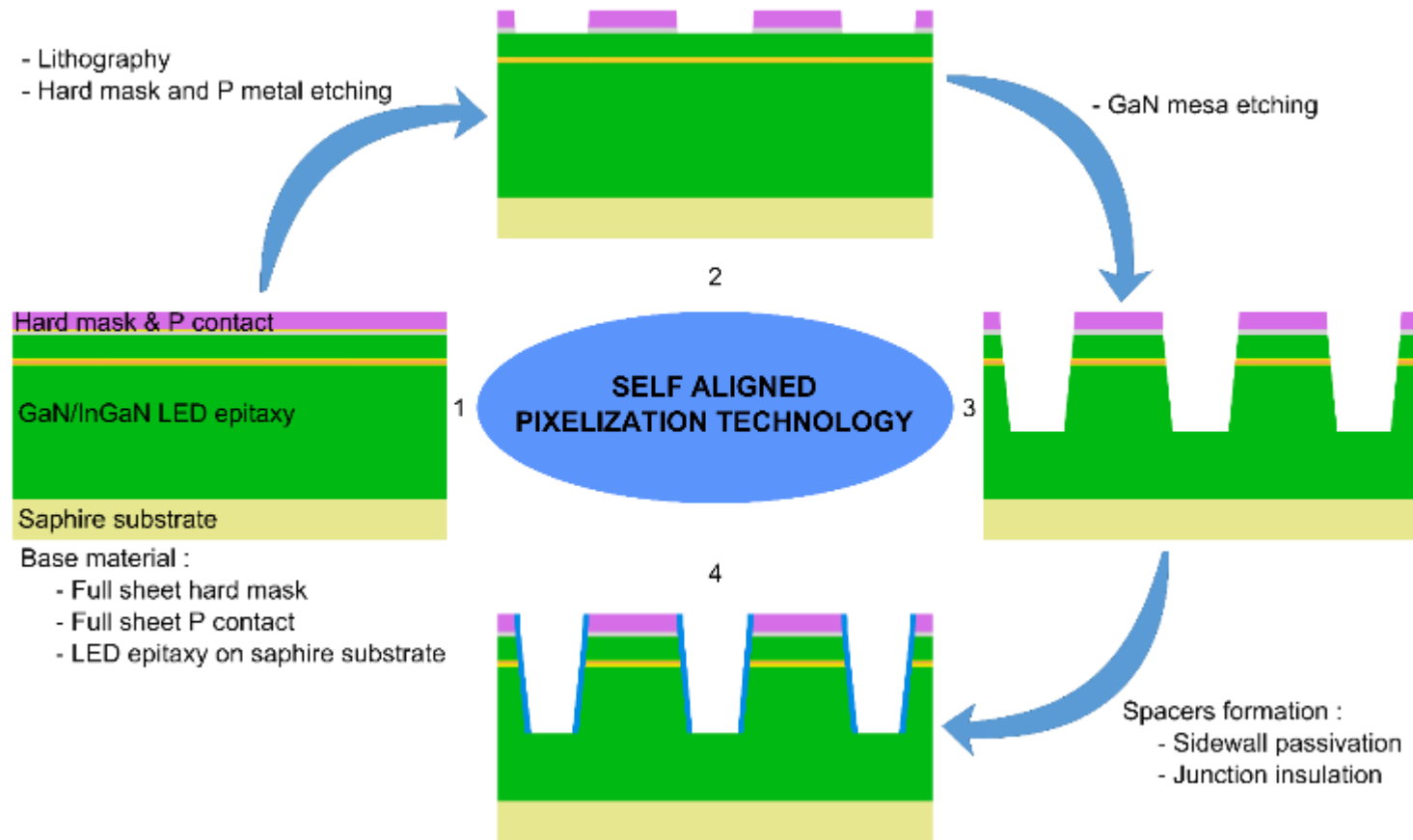
Mesa  
 Metals P/N  
 Insulations

### Challenges:

- Epitaxy quality
- Contacts
- ...Small-pitch

## DEVELOPMENT OF 10 $\mu\text{M}$ PITCH GAN LED ARRAY

- Self aligned technology

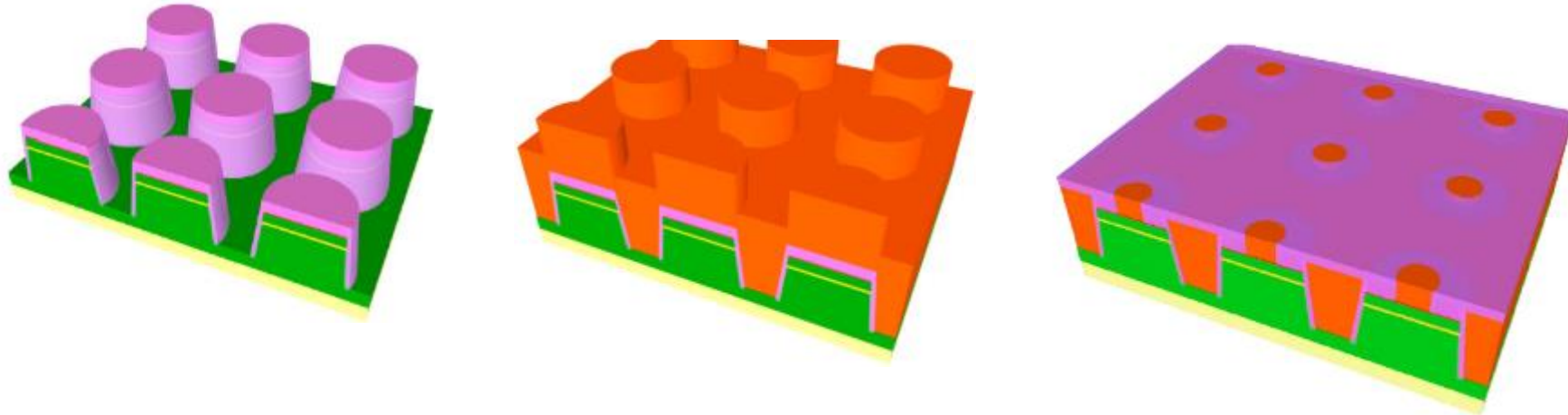


L Dupré et al, « *Processing and characterization of high resolution GaN/InGaN LED arrays at 10 micron pitch for micro display applications* », Photonics WEST 2017 – SPIE OPTO 2 Feb 2017

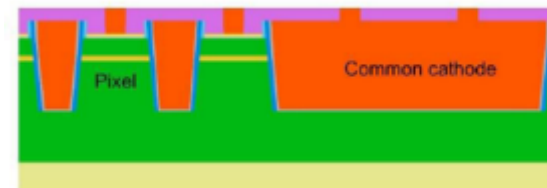
# LED MICRODISPLAYS FABRICATED WITH HYBRIDIZATION TECHNOLOGY

10- $\mu\text{m}$  pitch microLED array fabrication:

GaN LED array: 4-in. sapphire substrates.



- Damascene
- Self-aligned
- Common cathode with metal grid



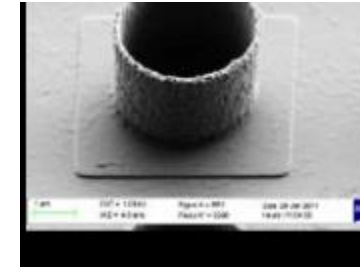
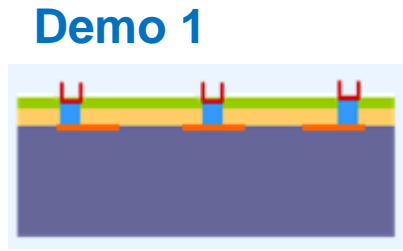
- 10  $\mu\text{m}$  pitch
- High performance



# HYBRIDIZATION OF 10 μM PITCH GAN LED ARRAY DEMO GEN 1

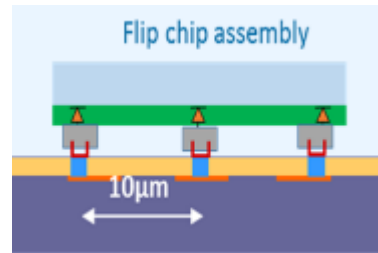
## Fabrication of silicon interconnect

- patterning an interconnect network,
- patterning metal pads,
- depositing microtubes on the pads

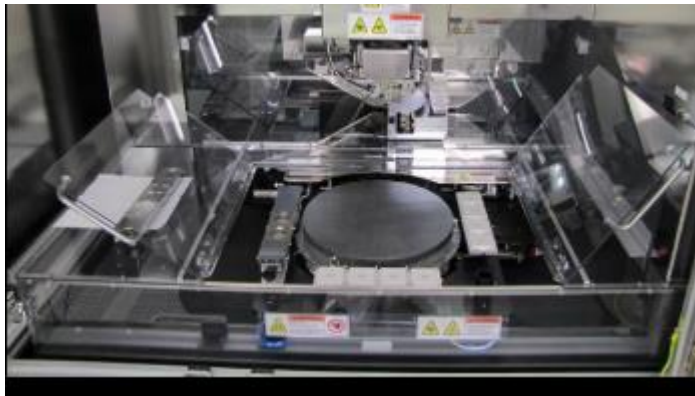


## Hybridization of display device

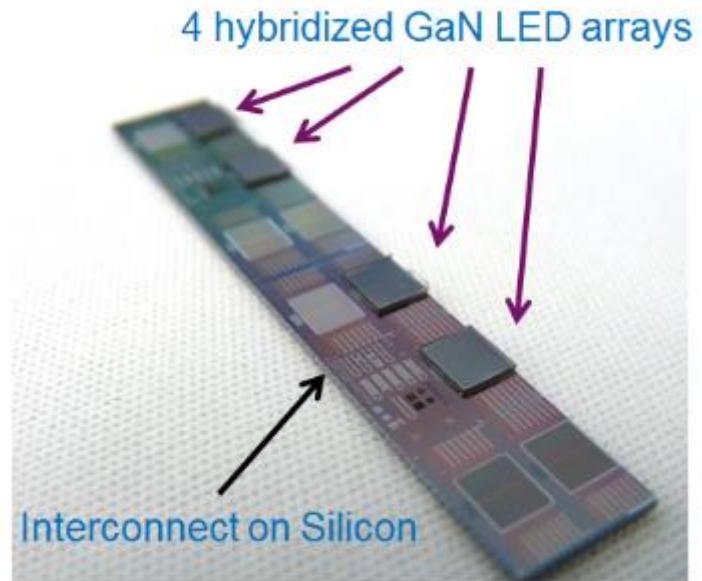
Die (GaN) to wafer process



## GaN arrays hybridized on Si at a pixel-pitch of 10 μm



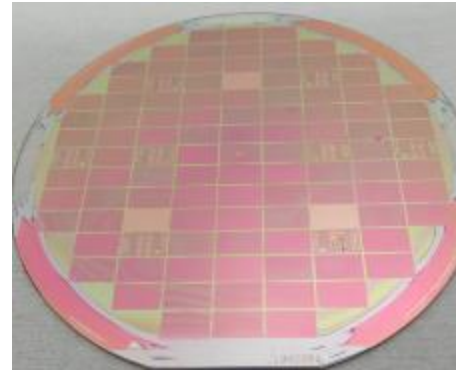
SET FC300  
+ microenvironment → limit the particulate contamination on the wafer during the chip-to wafer bonding.



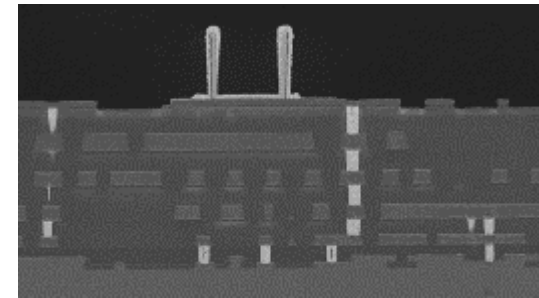
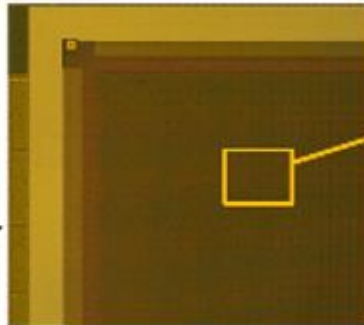
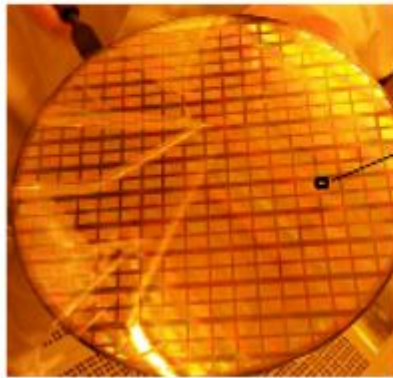
# DEMO GEN 2: ACTIVE-MATRIX GAN LED MICRODISPLAY

- GaN array:

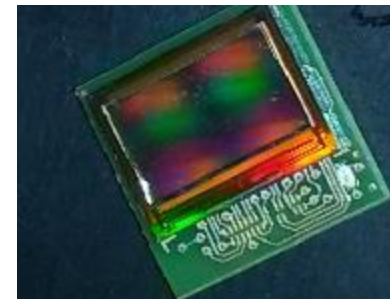
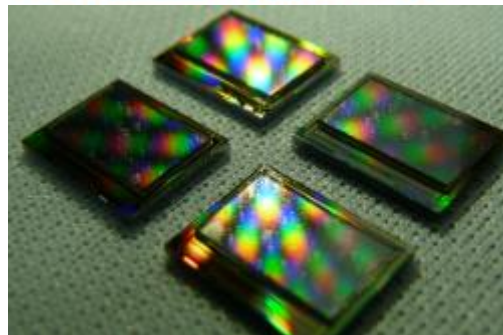
873 x 500 pixels  
10  $\mu\text{m}$  pitch



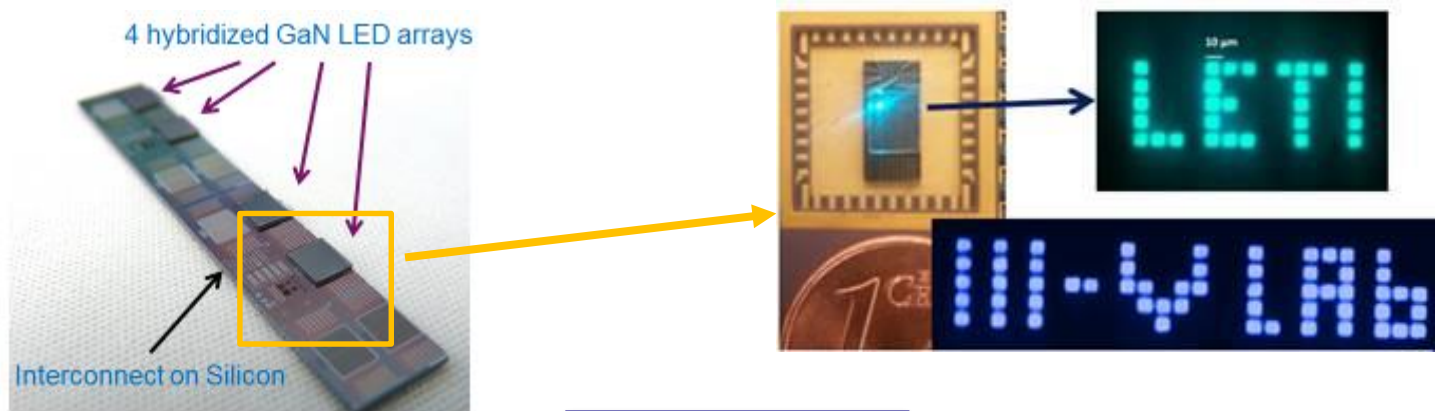
- CMOS active-matrix:



- Hybridization:

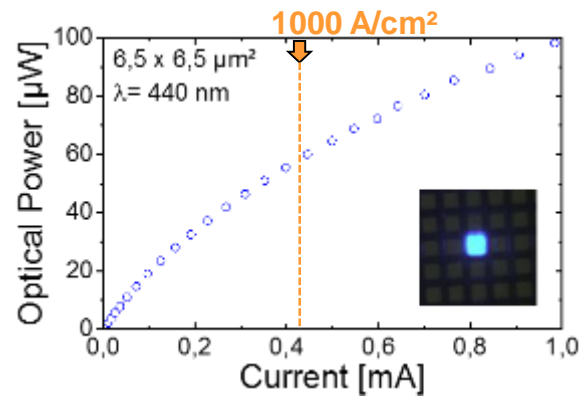


# DEMO GEN 1: CHARACTERIZATION

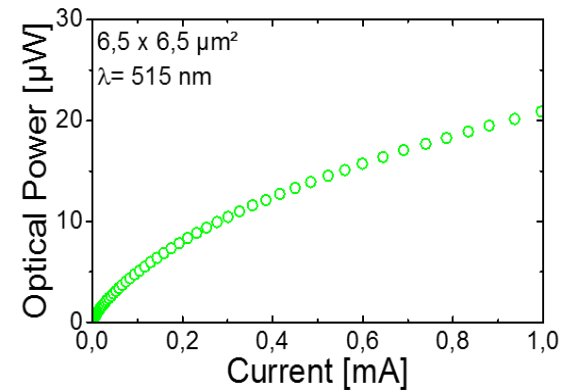


Optical power

Blue LEDs:



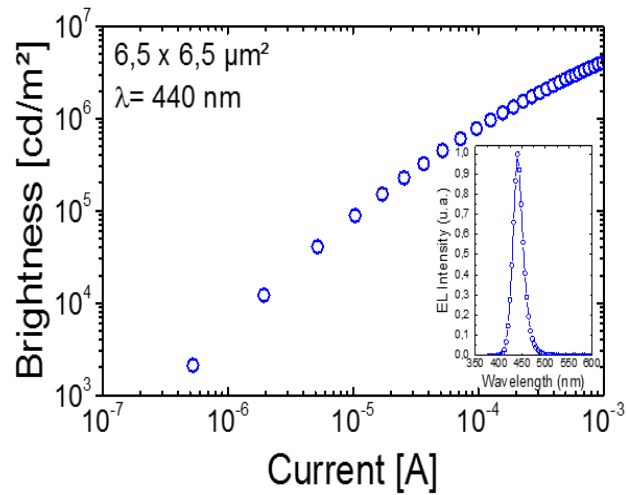
Green LEDs:



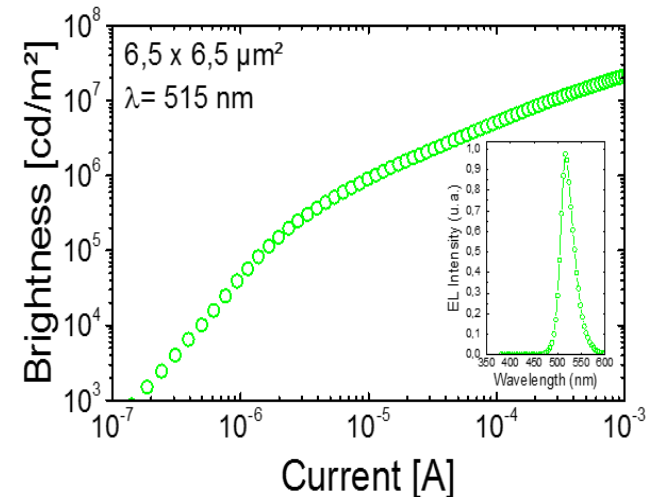
# DEMO GEN 1: CHARACTERIZATION

## Brightness

Blue LEDs:



Green LEDs:



	Wavelength (nm)	Brightness (Cd/m <sup>2</sup> )		max EQE (%)	max WPE W/W (%)
		at 10 $\mu\text{A}$	at 1 mA		
Blue Pixel	440	$\sim 10^5$	$\sim 4 \times 10^6$	9.5	7,8
Green Pixel	515	$\sim 10^6$	$\sim 2 \times 10^7$	5.9	3.4



# LED MICRODISPLAYS FABRICATED WITH HYBRIDIZATION TECHNOLOGY

## Active-matrix WVGA (873 x 500) LED demonstrators

### Monochrome Blue

« Motion GaN Blue »  
active-matrix WVGA  
10  $\mu\text{m}$  pixel pitch



### Monochrome Green

« Motion GaN Green »  
active-matrix WVGA  
10  $\mu\text{m}$  pixel pitch



**Brightness:**  
Blue: 300  $\text{Cd}/\text{m}^2$   
Green: 10 000  $\text{Cd}/\text{m}^2$

Full resolution...873 x 500 pixels  
Video...



# PIXEL PITCH: A KEY CHALLENGE

## Pixel-pitch in emissive microdisplays: (subpixel)

**OLED**  
(products)

**eMagin (2012)**  
0.86-in.  
1920x1200  
4.8  $\mu\text{m}$



**Microoled (2012)**  
0.61-in.  
1300x1044  
4.7  $\mu\text{m}$



**Sony (2014)**  
0.23-in.  
640x400  
3.9  $\mu\text{m}$



**Microoled (2014)**  
MDP03 0.39-in.  
1024x768  
3.8  $\mu\text{m}$



**iLED (GaN)**  
(prototypes)

**Texas Tech (2011)**  
0.31-in.  
640x480  
15  $\mu\text{m}$



**Ostendo (2014)**  
0.29-in.  
640x360  
10  $\mu\text{m}$



**Leti / 35 Lab (2017)**  
0.38-in.  
874x500  
10  $\mu\text{m}$

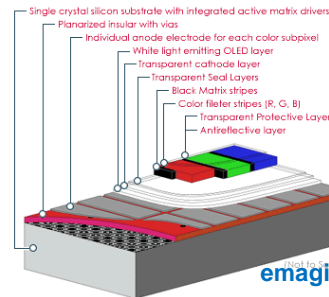


→ **Big gap!**  
→ **To be filled!**

### Why such gap?

### Fabrication approaches:

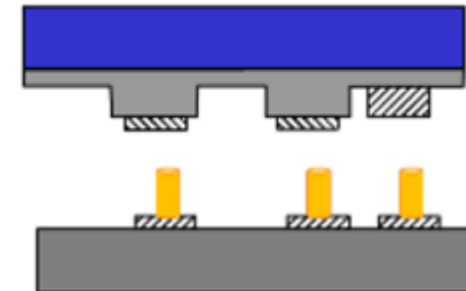
**OLED:**



→ **monolithic, full CMOS**

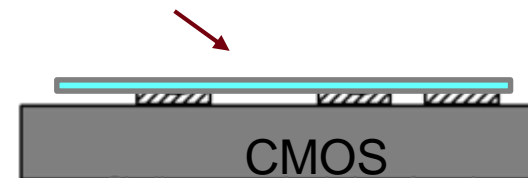
**iLED:**

- Separate fabrication
- Assembly step
- Alignment
- Bottleneck!



**Solution:**

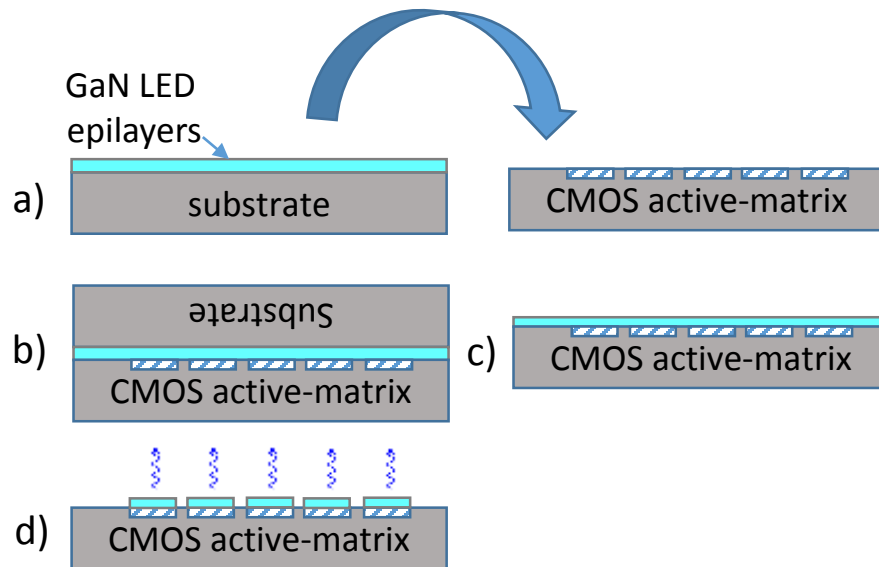
**Monolithic CMOS + GaN transfer:**



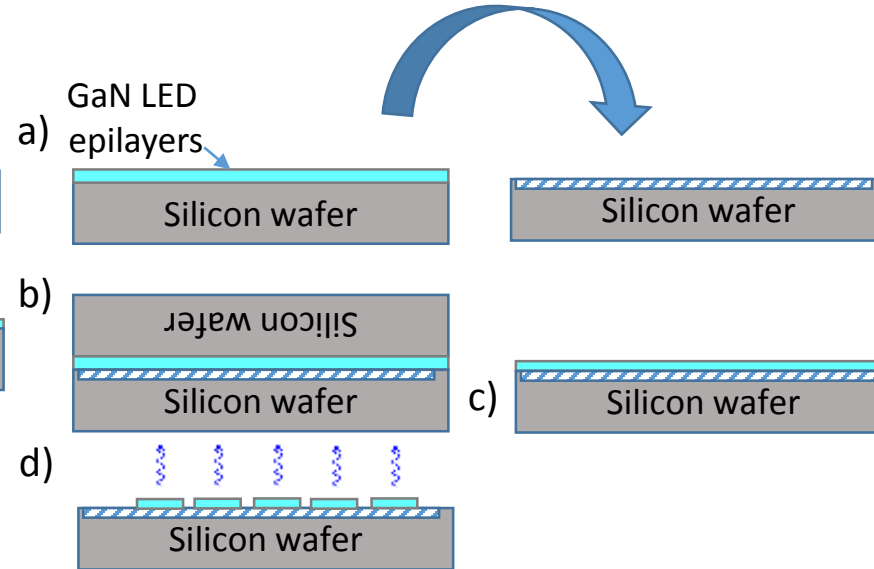
# NOVEL APPROACH FOR GAN MICRODISPLAYS

Novel approach: transfer of GaN on CMOS

Proof-of-concept/ feasibility demonstration:



→ No alignment  
→ Full CMOS

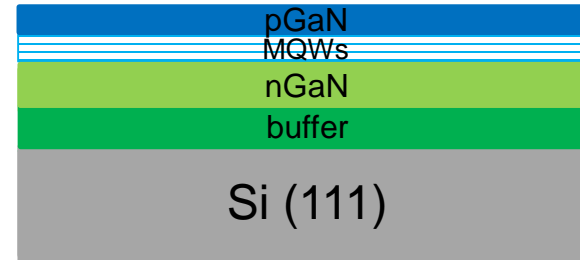


→ Integrate key steps / Led operation?  
→ Small pixel pitch?

# NOVEL APPROACH FOR GAN MICRODISPLAYS

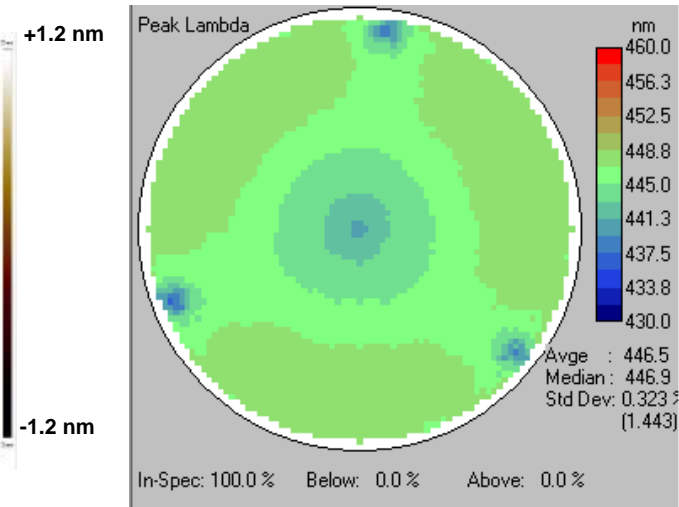
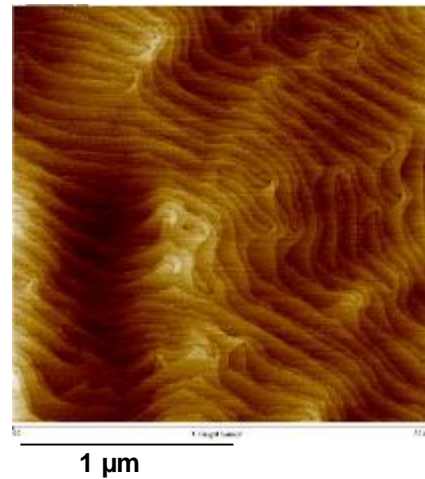
## Feasibility demonstration

### 1- LED epilayer on 200-mm Si



#### Key features:

- Bow (<math><50\mu\text{m}</math>)
- $\lambda$  homogeneity
- Surface roughness

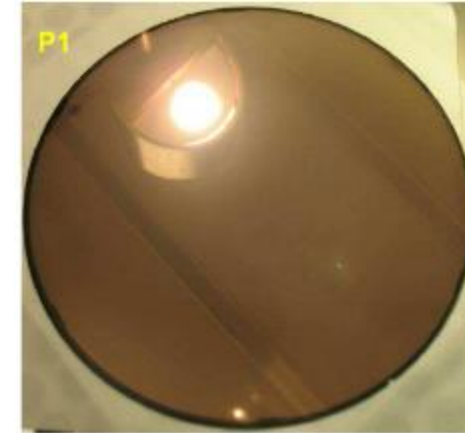
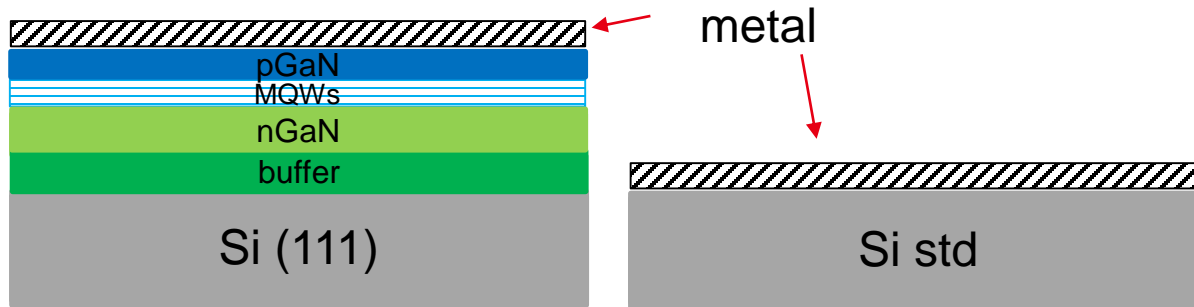


# NOVEL APPROACH FOR GAN MICRODISPLAYS

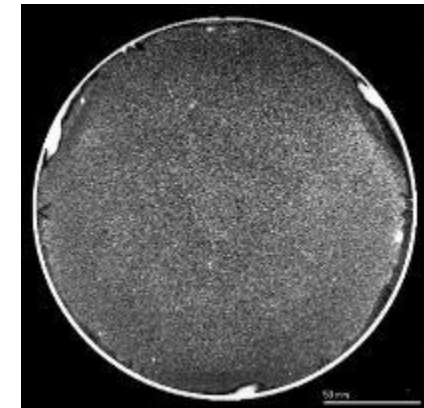
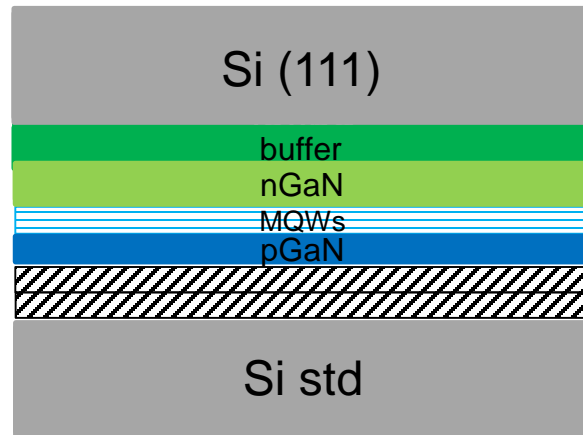
## Feasibility demonstration

### 2- Direct bonding on 200-mm Si

Metal deposition



Bonding

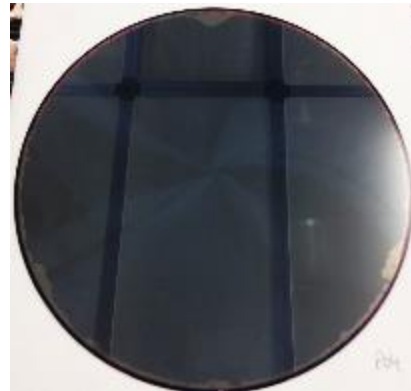
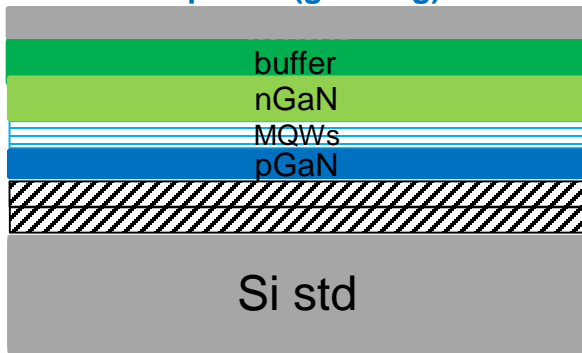


# NOVEL APPROACH FOR GAN MICRODISPLAYS

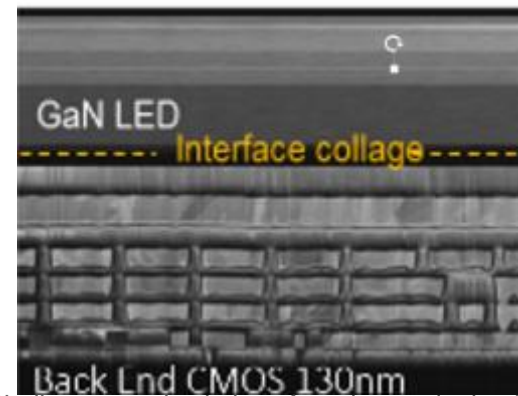
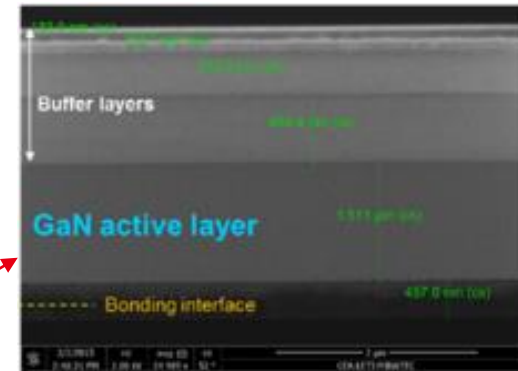
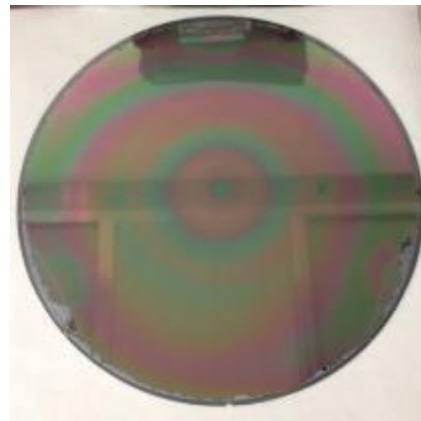
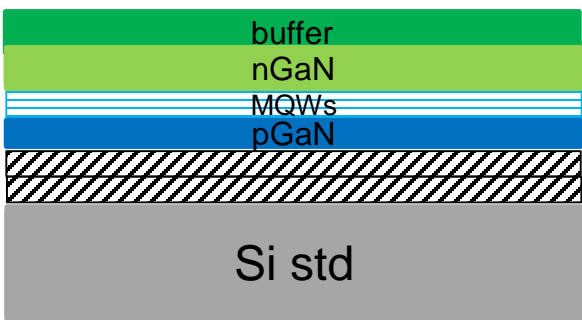
## Feasibility demonstration

### 2- Direct bonding on 200-mm Si

Silicon removal: partial (grinding)



Silicon removal: full

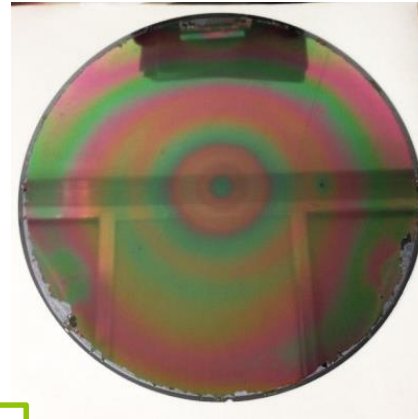
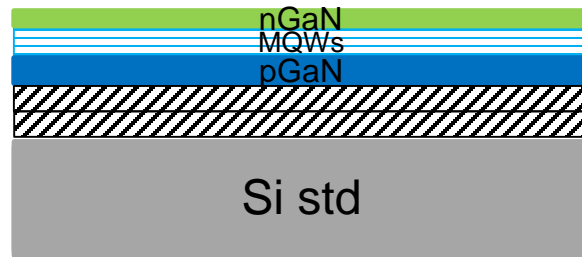


# NOVEL APPROACH FOR GAN MICRODISPLAYS

## Feasibility demonstration

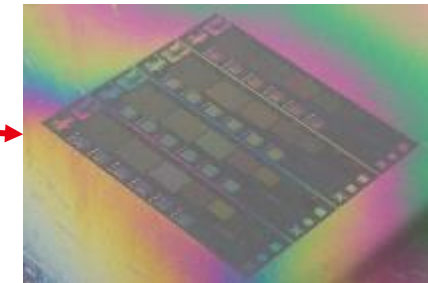
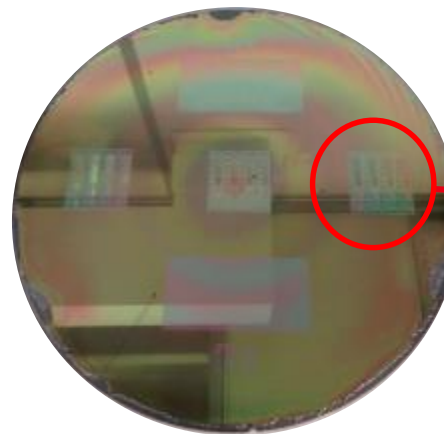
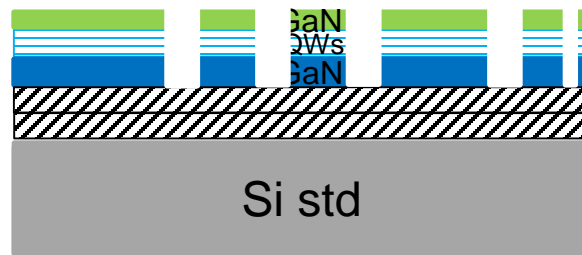
### 2- Direct bonding on 200-mm Si

Buffer removal: stop on N+



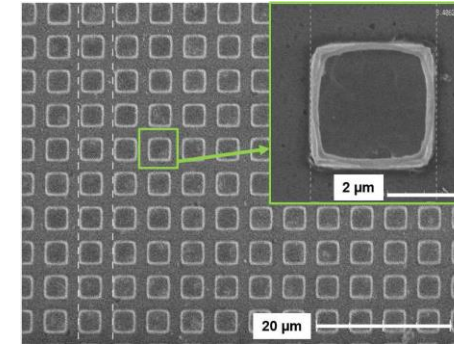
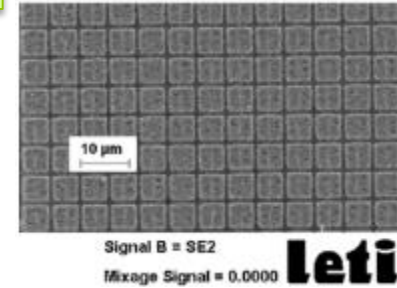
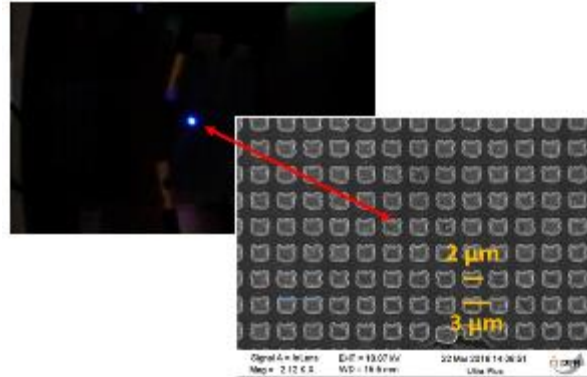
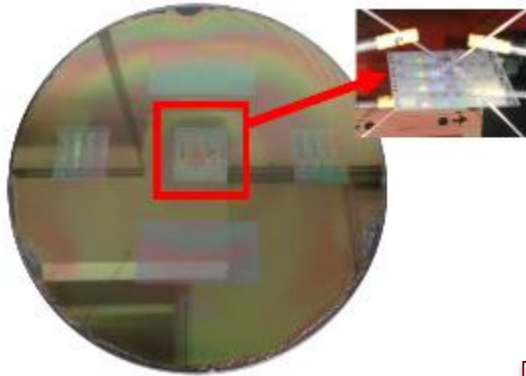
### 3- micro-LED patterning

High precision microLED patterning  
Plasma etch

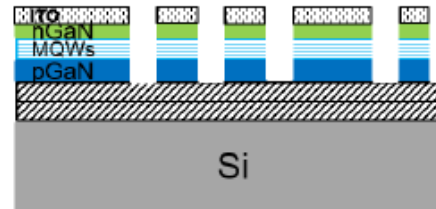
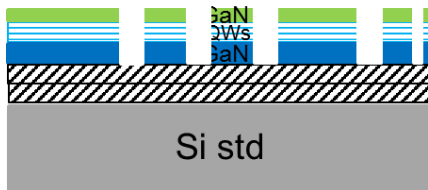


# NOVEL APPROACH FOR GAN MICRODISPLAYS

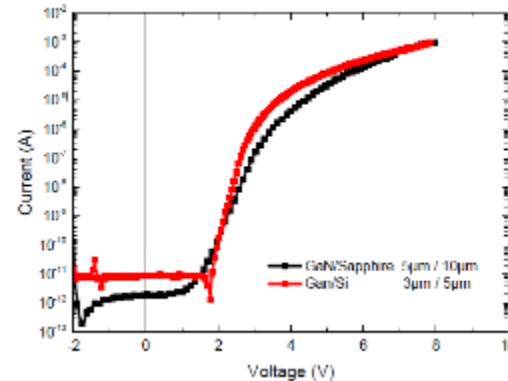
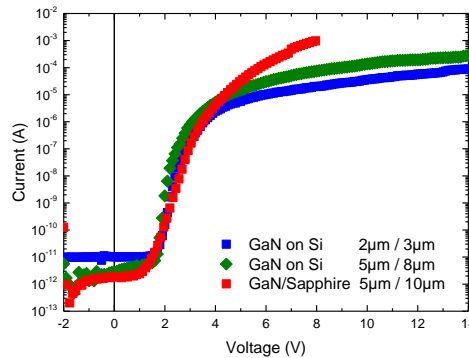
## Feasibility demonstration



With ITO:



I (V) curves:

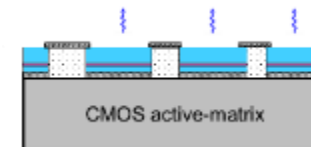


- MicroLEDs operate after transfer process and post processing (patterning)
- Record pixel-pitch GaN microLED array (3 μm)
- Good Electrical characteristics

→ Proof-of concept made

Next steps::

- Active-matrix prototypes





# TECHNOLOGICAL BRICKS

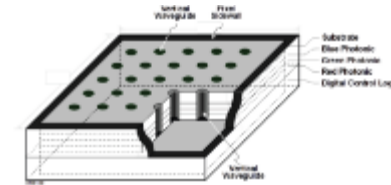
## THE COLOR CHALLENGE

- 3 colors on same wafer
- small pitch (10 / 5 / 3  $\mu\text{m}$ )
- crosstalk

### Direct generation:

- Stack of Three LEDs (Ostendo):

Clever, but \$\$\$



- Selective Area Growth (SAG)
- Nanowires
- InGaNOS

→ Medium/Longterm

### Color conversion:

Phosphors, QDs

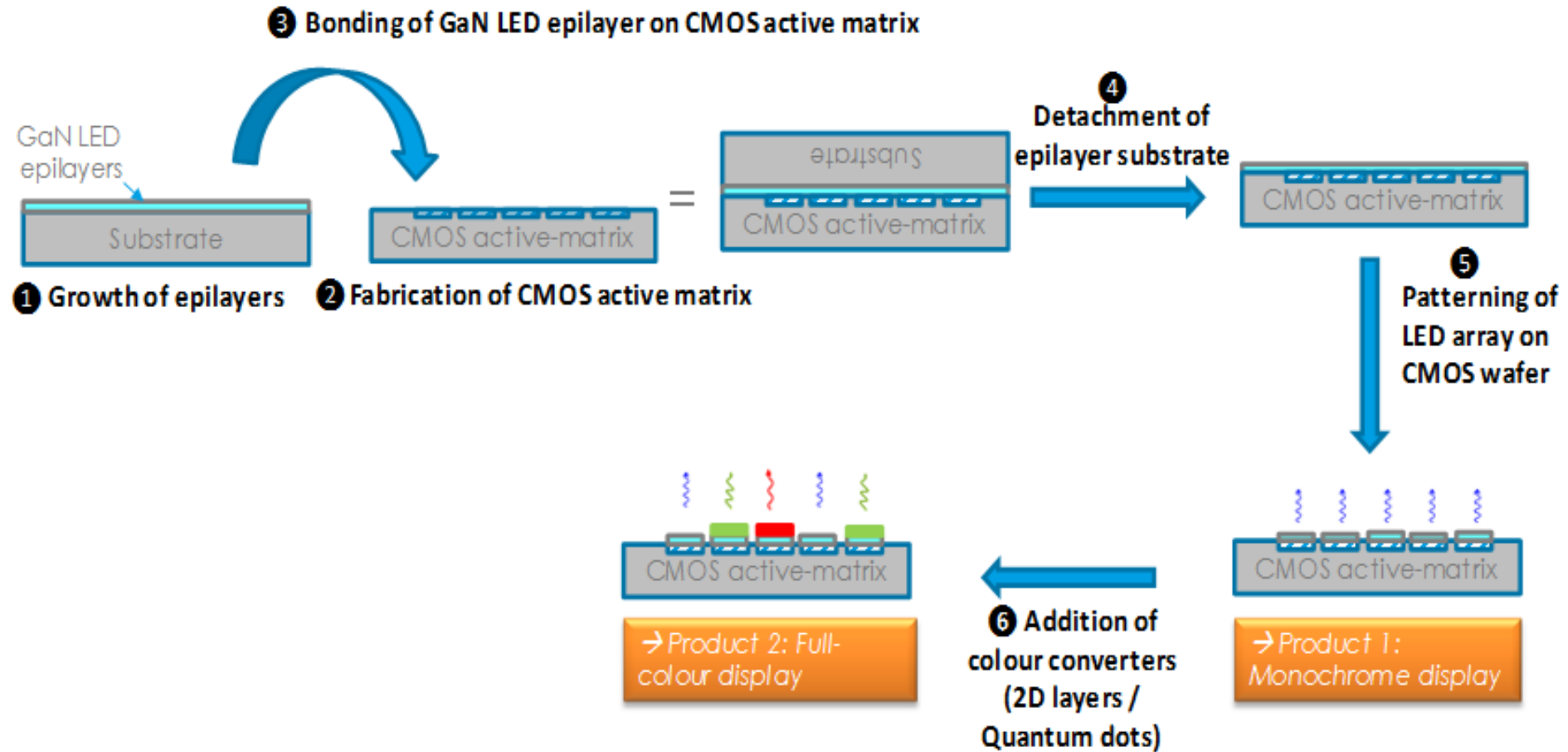
- Existing materials /Suppliers
- Good color saturation
- Lifte time?
- Pattern?

2D layers

→ MQWs Green : InGaN/GaN/sapphire

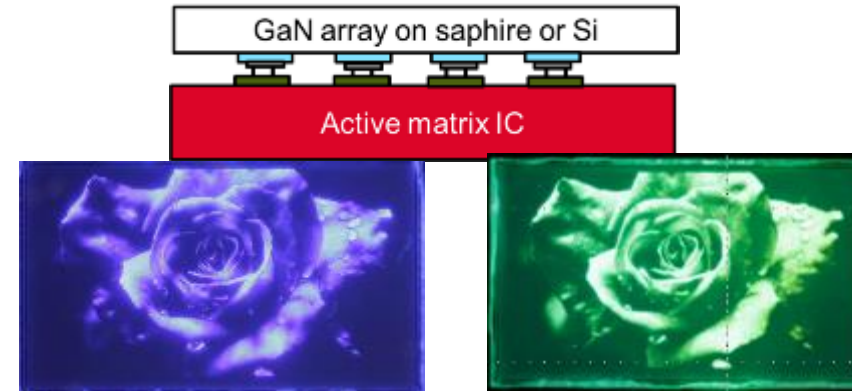
→ MQWs Red : InGaAlP/InGaP/GaAs

## Overall process / approach

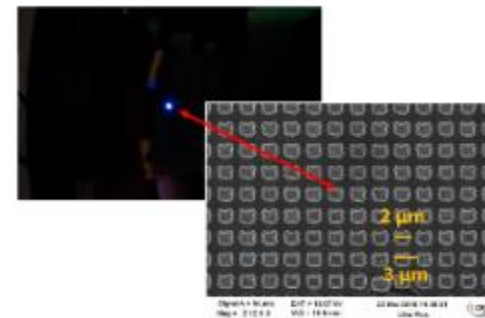


2 technologies are developed for making high brightness GaN microdisplays :

- **Hybridization technology:**
  - full active matrix WVGA, 10  $\mu\text{m}$  pitch
  - can address some applications



- **Monolithic technology:** proof-of-concept made.
  - Advantages:**
    - very small pixel pitch
    - suitable for colour
    - suitable for any other feature: extraction enhancement, emission direction, ...
    - full CMOS (industrialization, cost, ..)

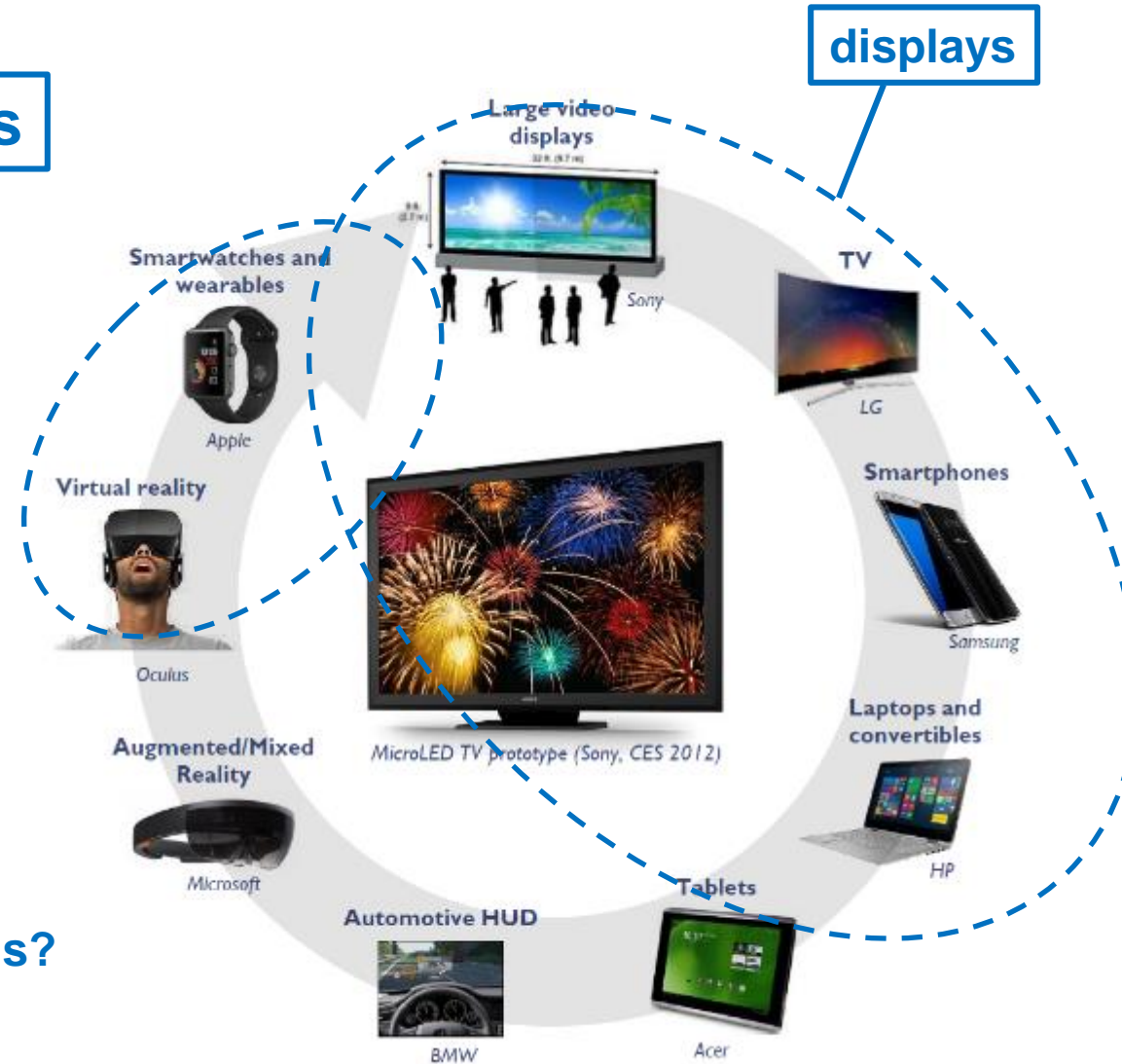


- **Some challenges remain....color, ...**

- ❑ Introduction
- ❑ Challenges and (some) solutions for GaN microdisplays
  - ❑ LED microdisplays fabricated with hybridization technology
    - ❑ Gen1 and Gen2 GaN microdisplay demonstrators
  - ❑ LED microdisplays fabricated with direct bonding technology
  - ❑ Other challenges for microdisplays
- ❑ Challenges and (some) solutions for MicroLED displays
  - ❑ microLED Transfer process
  - ❑ microLED display driving
- ❑ Conclusion

# THE DISPLAY WORLD(S)








## MicroLED displays



What are the motivations?

# WHY MICROLED DISPLAYS?

Depends on application....

	Smartwatch 	Smartphone 	Laptop and tablets 	TVs 	VR 	AR 	Automotive HUD 	Video displays 
Energy consumption	5	4	4	1	3 (un-tethered)	5 (un-tethered) [1]	1	4
High Pixel Density	2	2	1	1	5	5	0	0
Color Gamut	2	2	3	5	4	4	1	4
Brightness	5	4	3	4	0	5	5	4
Contrast	3	3	3	5	3	3	3	4
Refresh rate	1	1	2	5	5	4	1	1
Long lifetime	1	1	2	2	2	2	5	5
Flexible	3	3	0	0	1	1	1	3
Overall attractiveness	22	20	17	23	24	29	17	25

[1]: expect longer use periods than VR

1 - Not very important or differentiating  
 2 - Important  
 3 - Very important

4 - Critical  
 5 - Strong differentiator

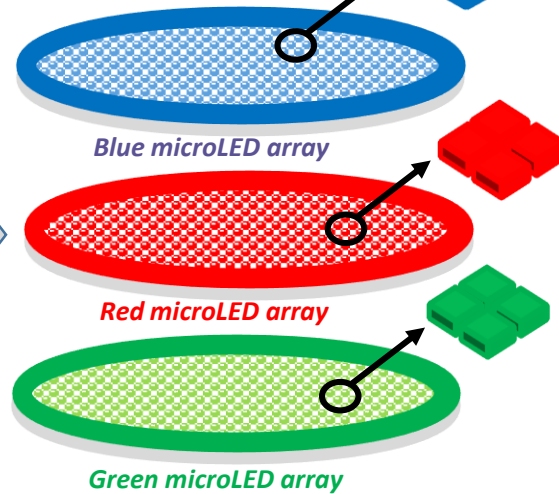
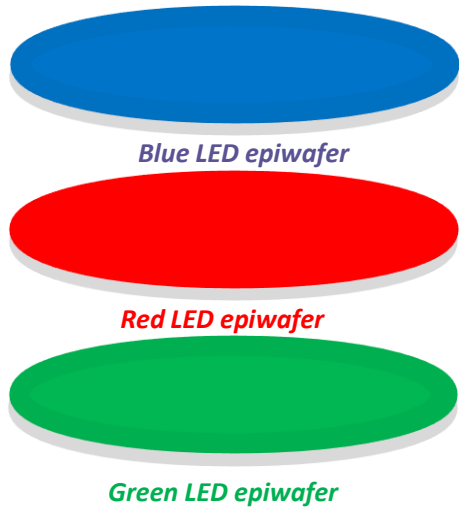
Image quality is the main target

# INTRODUCTION : LED DISPLAYS: GENERAL APPROACH

## 1- microLEDs fabrication

Pitch: 5-10  $\mu\text{m}$

RGB microLED  
Fabrication



Singulation

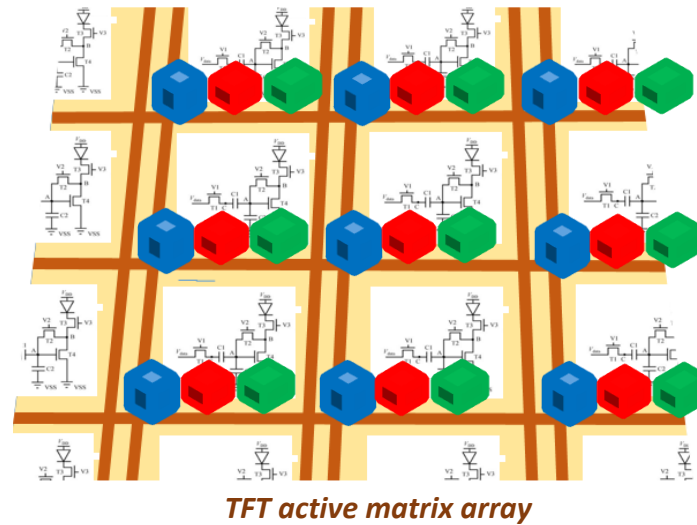
## 2- Transfer on TFT

Pitch: 100- 500  $\mu\text{m}$

Blue transfer

Red transfer

Green transfer

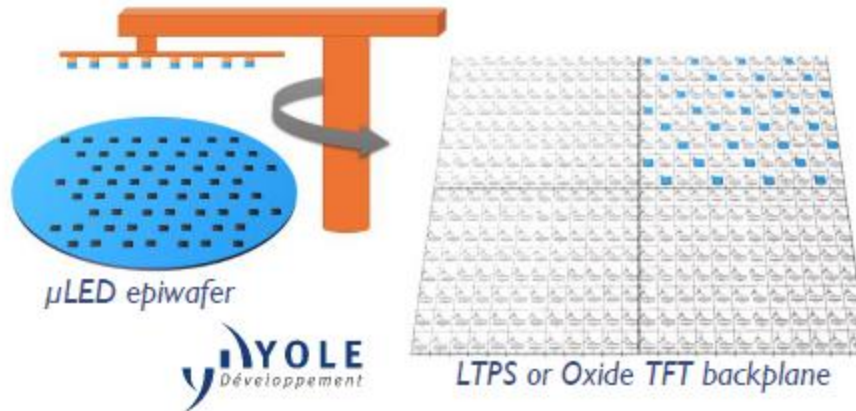
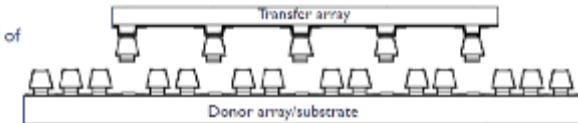


# CHALLENGES IN THE TRANSFER PROCESS

## Low to Mid Pixel density: Pick and Place



- Pick up pitch = 1/3<sup>rd</sup> of donor pitch.
- All pick up heads activated



### Principle:

- 1-Select a series of MicroLEDs on donor (→ other pitch)
  - 2-Transfer onto TFT plate (large pitch)
  - 3-Select a new series
  - 4- Transfer on new field on TFT
- Etc..
- .....Repeat for other colors

### 2 key features:

- 1- ensure mechanical contact + electrical contact
- 2- numbers: TV HD: 6+ millions; 4K: 24 M... → go fast, yield



## MICROLED DISPLAYS: KEY CHALLENGES

### → RGB microLED performance

- Brightness, EQE, ...
- For very small size devices
- For the three colors...

How LETI addresses them?

- develop high quality RGB microLEDs
- investigate size reduction effects

### → transfer process:

- Yield (99.9999...)
- Throughput (mass production)
- Cost (consumer)
- Connection?

- Evaluate transfer process with microtube technology
- Evaluate transfer process with reduced step approach

### → microLED display driving

- High brightness means ...high currents
  - Led homogeneity issues: brightness , wavelength, ...
- *Driving very challenging*

- Evaluate a disruptive approach where microLEDs are CMOS driven

- ❑ Introduction
- ❑ Challenges and (some) solutions for GaN microdisplays
  - ❑ LED microdisplays fabricated with hybridization technology
    - ❑ Gen1 and Gen2 GaN microdisplay demonstrators
  - ❑ LED microdisplays fabricated with direct bonding technology
  - ❑ Other challenges for microdisplays
- ❑ Challenges and (some) solutions for MicroLED displays
  - ❑ microLED Transfer process
  - ❑ microLED display driving
- ❑ Conclusion

# CHALLENGES IN THE TRANSFER PROCESS

Multiple technologies have been proposed to exert the pick up force on the die:

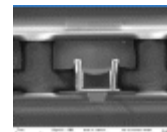
Electrostatic MEMS	Elastomer stamp	Electrostatic Stamp	Magnetic/Electromagnetic	Adhesive	Fluidic Assembly
LuxVue-Apple	U of Illinois, X-Celeprint, Semprius, Cooledge, AUO, CSOT, ITRI	Cooledge, AUO	Cooledge, PlayNitride, ITRI	PlayNitride, Intel	Nth Degree, Sharp, PSI
<p>FIG. 9</p>	<p>FIG. 5</p>	<p>FIG. 5</p>	<p>FIG. 5</p>	<p>FIG. 5</p>	<p>FIG. 5</p>
<p>The LuxVue process uses an electrostatic pick up head. The die is released via the local phase change of a bonding layer (e.g. from solid to liquid or at least a more malleable state).</p>	<p>The X-Celeprint process uses Van Der Waals forces. The die is released by breaking an anchor. Cooledge process also suggest release by breaking anchor or through laser lift of.</p>	<p>A transfer stamp is charged with a spatial pattern of electrostatic charge. The stamp may be bulk charged and then selectively discharged using irradiation through a patterned mask.</p>	<p>The stamp is an array of magnetic or electro-magnetic transfer posts (MEMS form or passive stamp). LED die are magnetized by coating and patterning a suspension of magnetic particle in photoresist.</p>	<p>The stamp is a stretchable adhesive film. The <math>\mu</math>LED are picked up by the film which is then stretched along the X and Y direction to match the pitch of the receiving substrate before release of the die.</p>	<p><math>\mu</math>LED in a suspension in a fluid are deposited at the surface of substrate featuring micro cavities and/or circuit traces. The <math>\mu</math>LED are dipoles and can be aligned with an electromagnetic field of the die.</p>

## 1- Connection

In general, bonding of microLEDs on final substrate (TFT) is very tricky (release from transfer carrier)

In most cases, electrical connexion is not made at this step → needs further processing

*A connection approach where strong mechanical bonding + electrical connection are provided in a single step is highly desirable*

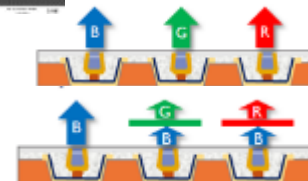


**It exists!**

## 2- Throughput

In general, only one color is transfered at a time → long

*Why not transfer three colors in one step?*



→ 3 transfers

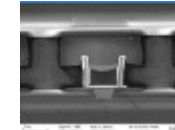
→ 1 transfer

# CHALLENGES IN THE TRANSFER PROCESS

## Transfer process with microtube technology

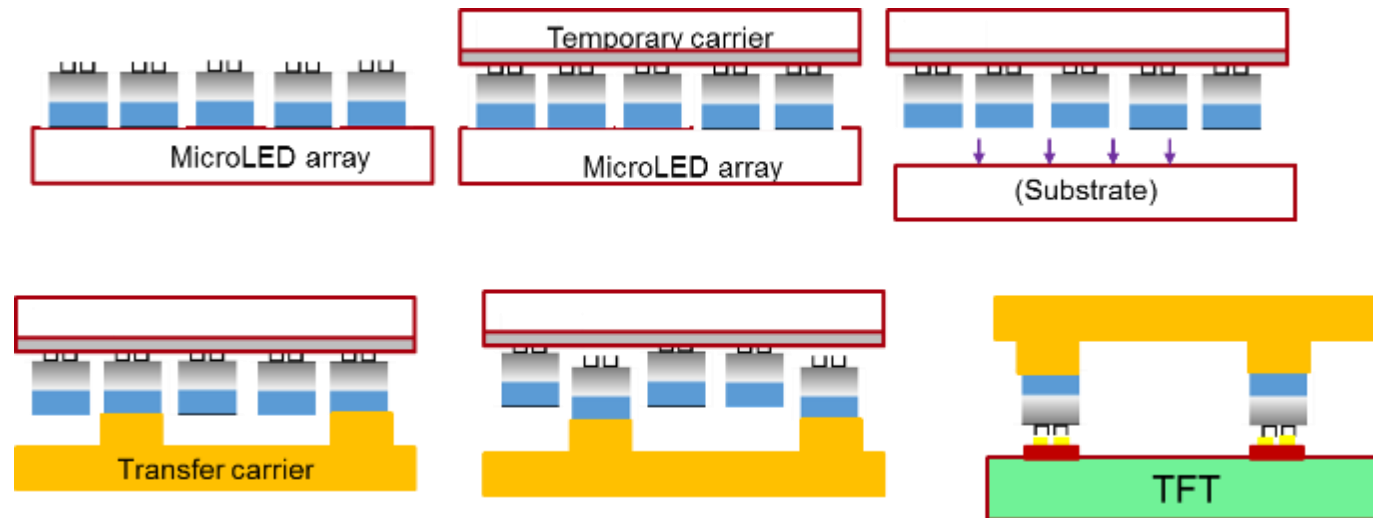
### Key advantages:

- Microtubes makes both electrical and mechanical connection
- Reliable / proven technology for microdisplays / sensors
- Room temperature process



Microtubes can be grown on microLED wafer  
→ Easy process for the connecting pad on the TFT side

### Example of implementation:

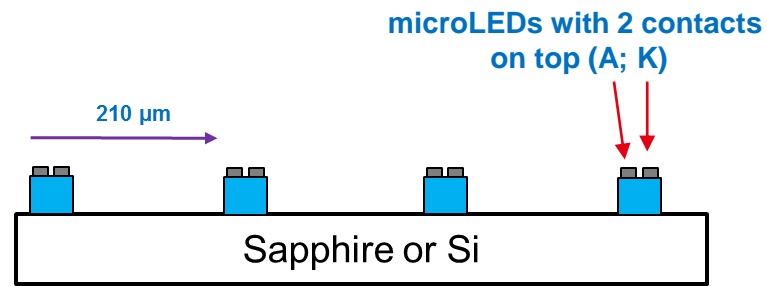


# CHALLENGES IN THE TRANSFER PROCESS

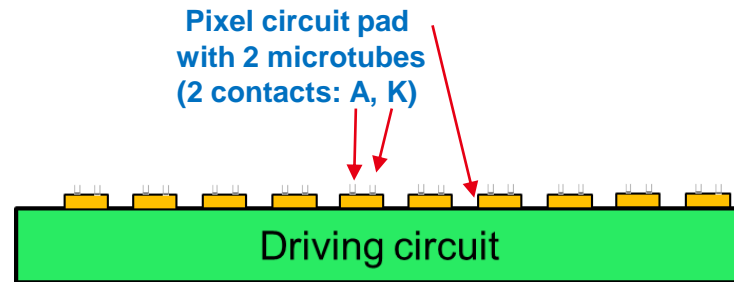
## Transfer process with microtube technology

### Proof of concept

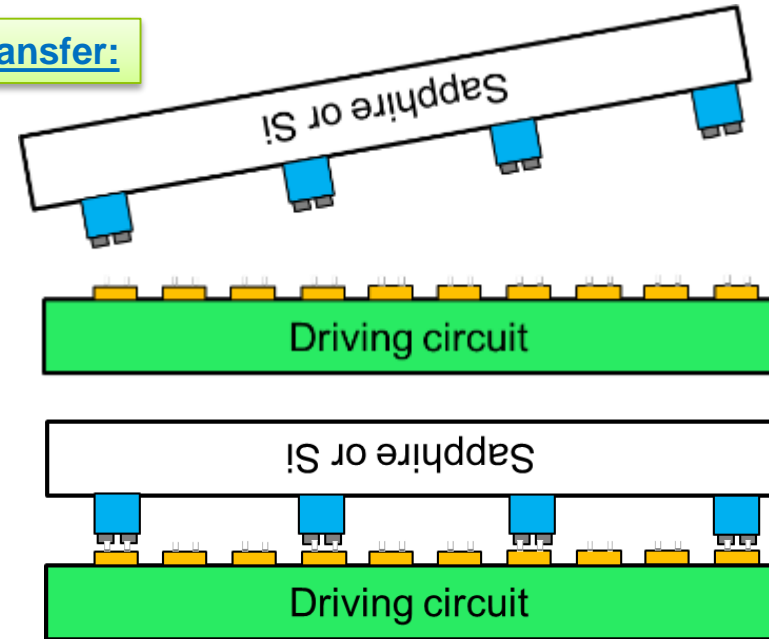
#### 1- MicroLED fabrication:



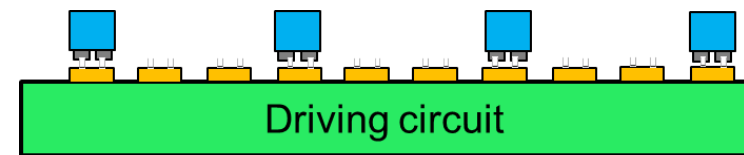
#### 2 - Driving circuit fabrication:



#### 3- Transfer:

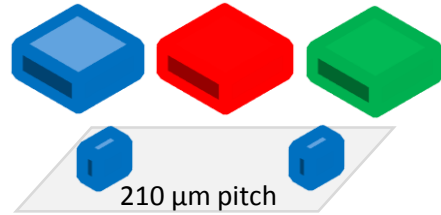


#### 4- Substrate removal:

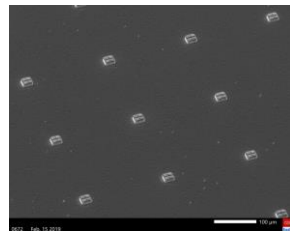


# Proof of Concept for large area display on passive backplane

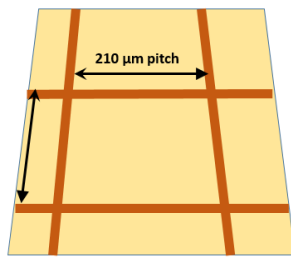
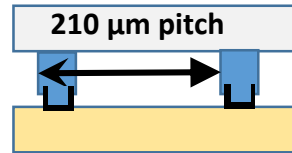
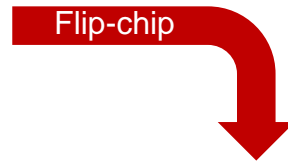
MicroLED available in blue, red and green



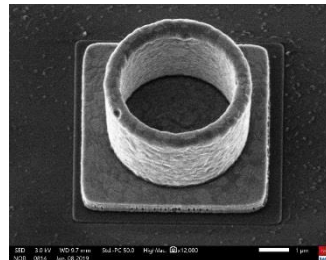
4" epi wafer



microLED stamp

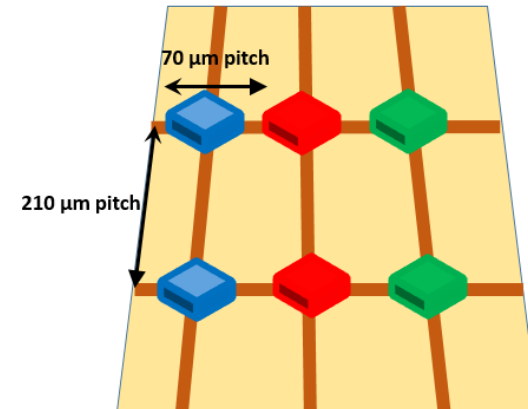
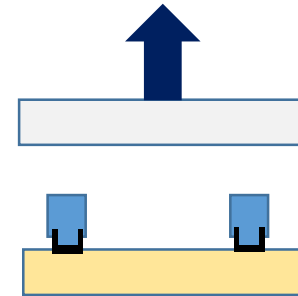


Passive backplane



Microtube

Epi-wafer removal for each color



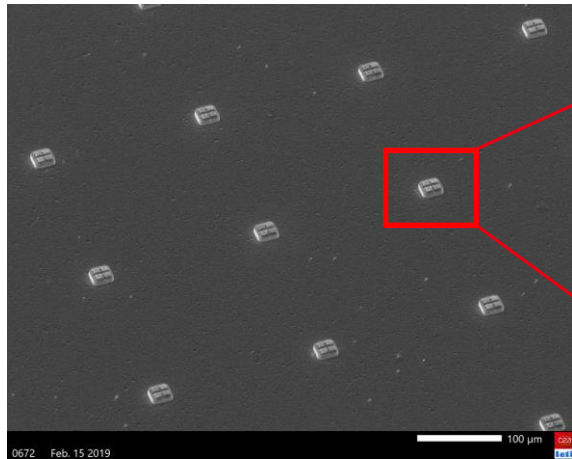
Passive backplane

# CHALLENGES IN THE TRANSFER PROCESS

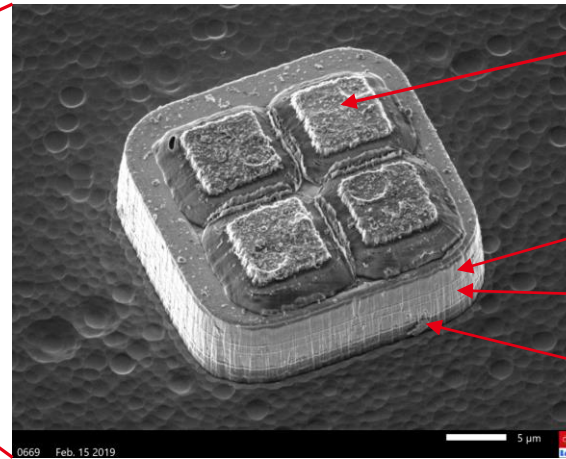
## Transfer process with microtube technology

### 1- MicroLED fabrication:

### Proof of concept



MicroLED array – 210µm pitch



Single MicroLED (25µm side)  
with 4 metallic pads on the top side

Metal pad for hybridization

P-type GaN

N-type GaN

Silicon pedestal

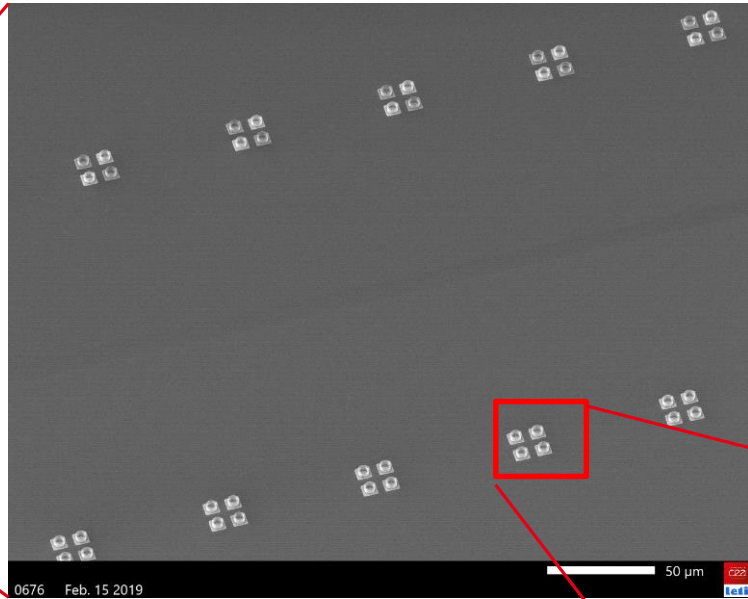
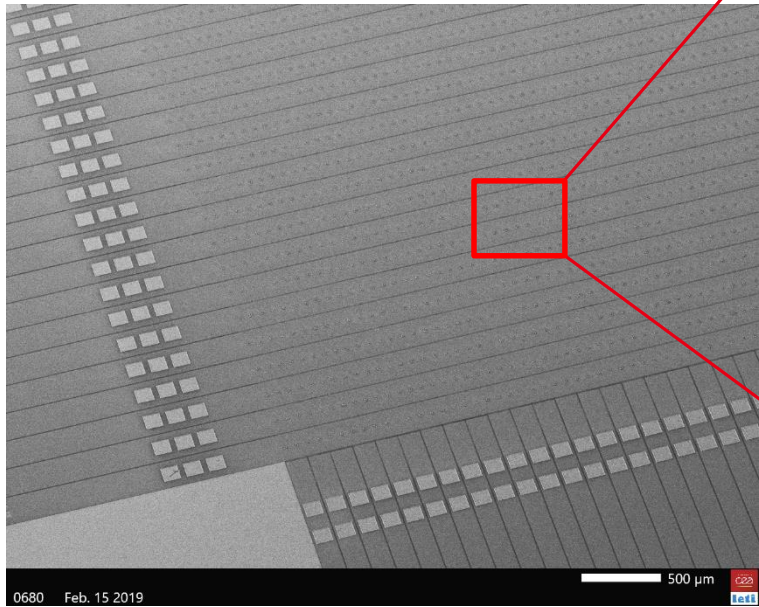
J. Bernard et al., Display week, 2019

### Process upside down (GaN on Silicon)

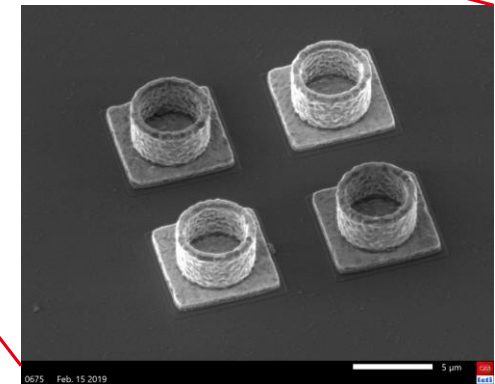
- Patterning and deposition the N-contact metal down to N-type GaN + insulation
- Patterning and deposition the P-contact metal + insulation
- Patterning and deposition the vias and metal pad for hybridization



# PASSIVE BACKPLANE



Microtube with 10μm pitch

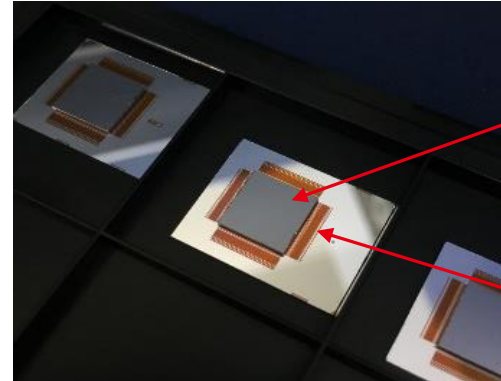


- **X, Y matrix**
  - 210μm pitch in Y and 70μm pitch in X for RGB
- **Standard silicon technology**
- **With microtubes on top side**

➤ 4 microtubes for mechanical stability



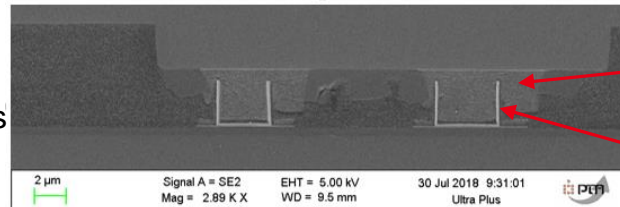
## HYBRIDIZATION



Stamp (64mm<sup>2</sup>) with MicroLEDs

Passive matrix with Microtubes

Cross section view  
of microtubes hybridize on pads

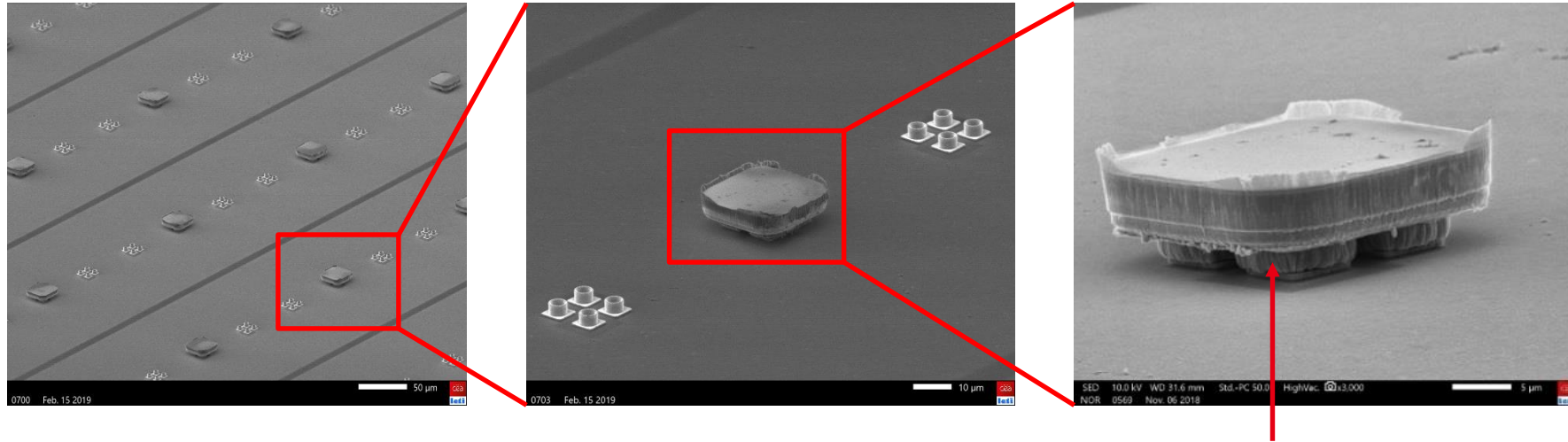


Pad for hybridization

Microtubes

- **Collective Flip-chip hybridization**
  - Transfert of 1600 microLEDs in 1 step

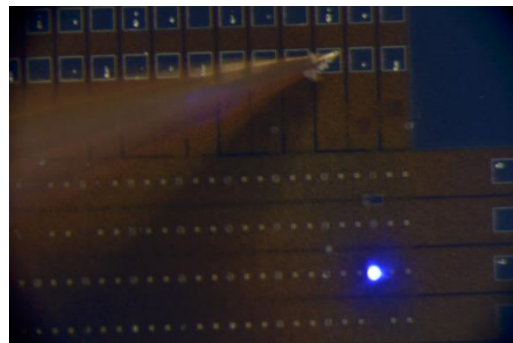
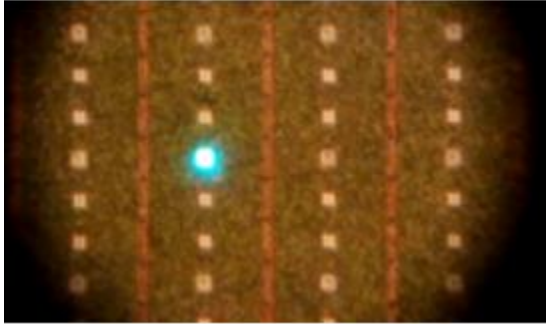
# MicroLED Liberation from epitaxial substrate



Microtube interconnections

- Liberation

## RESULTS



→ Microtube suitable for microLED display

Next steps:

- Full color transfer
- Transfer on Active matrix

➤ Operating in **green** and **blue**

- ❑ Introduction
- ❑ Challenges and (some) solutions for GaN microdisplays
  - ❑ LED microdisplays fabricated with hybridization technology
    - ❑ Gen1 and Gen2 GaN microdisplay demonstrators
  - ❑ LED microdisplays fabricated with direct bonding technology
  - ❑ Other challenges for microdisplays
- ❑ Challenges and (some) solutions for MicroLED displays
  - ❑ microLED Transfer process
  - ❑ microLED display driving
- ❑ Conclusion

- Challenges for driving microLED displays

# INTRODUCTION MICROLED DISPLAYS: KEY CHALLENGES

## 2- Driving electronics performance

New specifications

New technology / material

### New specifications:

**High resolution**

HD, 4K, 8K, ...

higher frame rates (60, 120 Hz,...)

→ *higher operating speed for the electrical driving at the pixel level.*

**High Dynamic Range (HDR)**

→ higher brightness

→ *higher levels of current to be supplied*

→ ***Driving electronics under new constraints***

# CHALLENGES IN THE MICROLED DISPLAY DRIVING

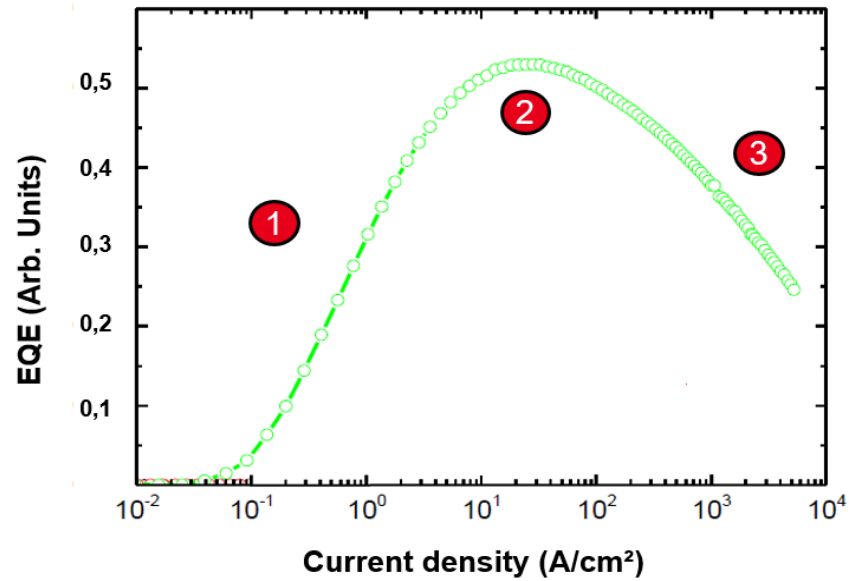
New technology / material

InGaN; AlInGaP

1-specific luminance response

2-Inhomogeneities / variability

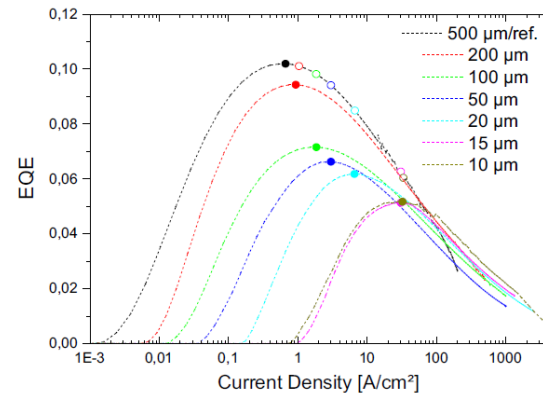
## specific luminance response



EQE as a function of current density for a 20-µm size blue-emitting InGaN microled

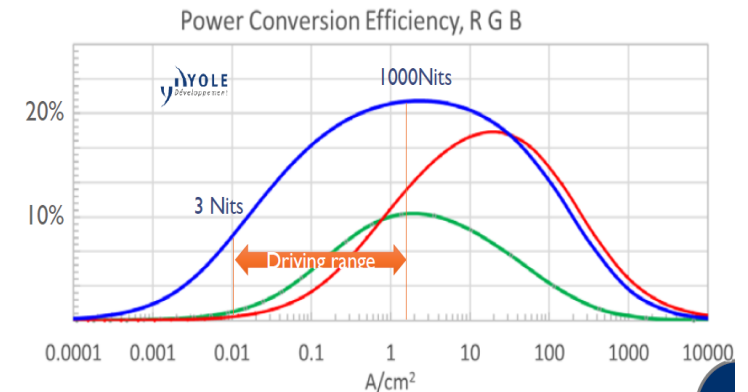
- 1 non-radiative recombinations, resulting from defects at the periphery of the devices
- 2 peak efficiency (Regime 2, obtained around a few A/cm)
- 3 Auger-effect

## Size-dependance



## How to drive?

## Color dependance



# CHALLENGES IN THE MICROLED DISPLAY DRIVING

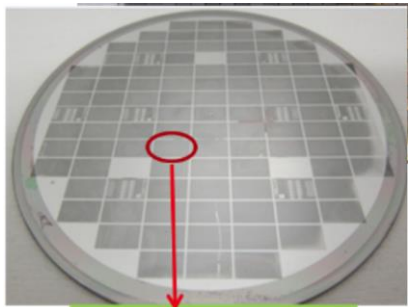
New technology / material

InGaN; AlInGaP

2-Inhomogeneities / variability

I-V-L curves: variability

GaN microLED arrays for microdisplays



Each die: GaN array :  
873 x 500 = 436 500 pixels  
at 10 μm pitch

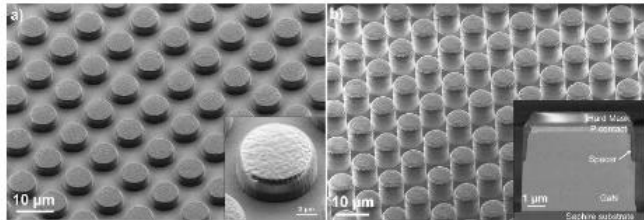
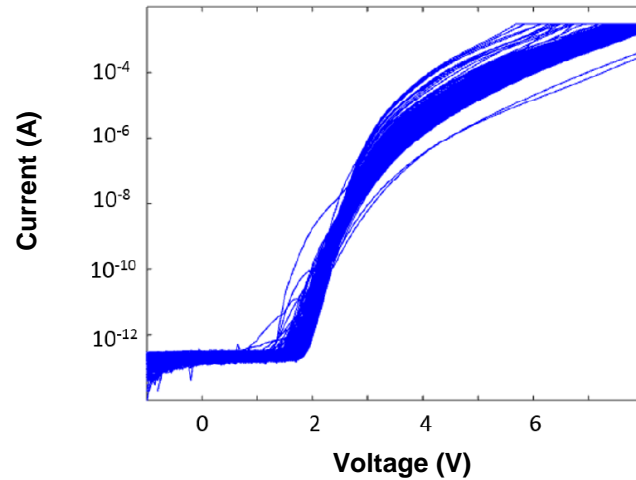


Figure 3. SEM images of 8 μm pixels at a pixel pitch of 10 μm after spacers formation. (a) The GaN mesa is 1 μm deep, inset is a zoom on a single μLED. (b) The GaN mesa is etched down to the sapphire substrate, inset is a cross sectional view of a pixel revealing the internal structure.

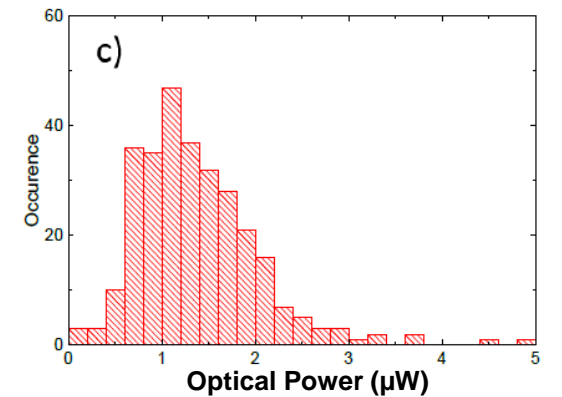
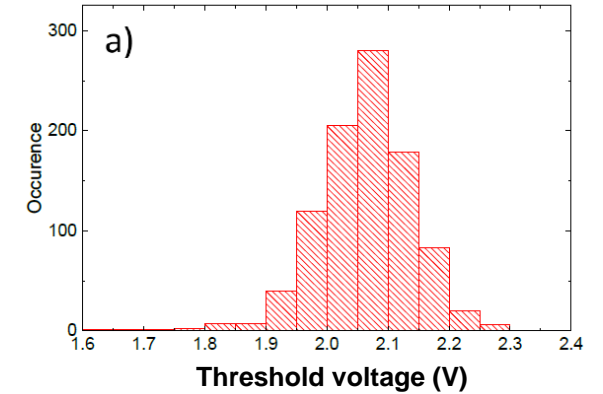
~ 1000 μLEDs tested on one matrix:  
1st Gen, 6 μm size, 10 μm pitch



Wavelength variability:

Addition of 3 primary colors

→ Each color very homogeneous (~1-2 nm) or compensated?





## CHALLENGES IN THE MICROLED DISPLAY DRIVING

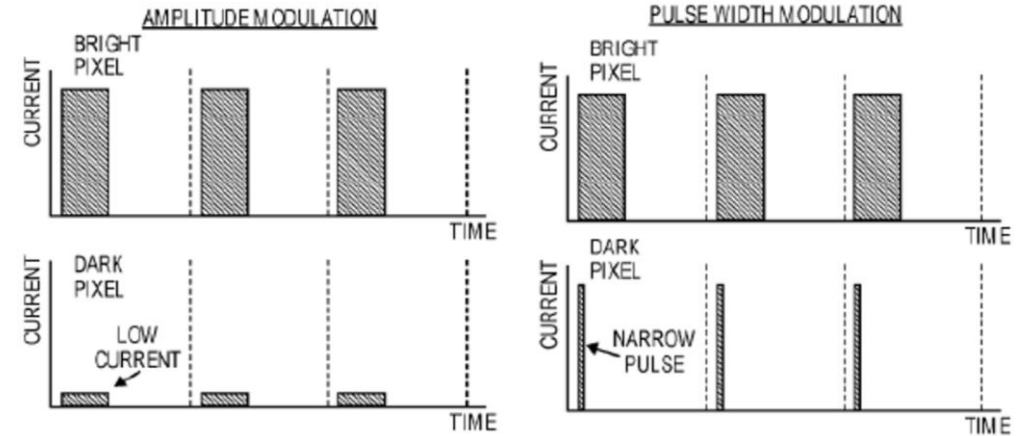
### Solutions for microLED display driving:

Analog amplitude modulation : not suitable

### Solution: Pulse Width Modulation (PWM):

→ fixed current

→ brightness level = duty cycle



Extremely fast switching : microLED device OK (nsec) → high bit rate/high gray scale.

Current density set at peak efficiency

No blue shift.

Combined with compensation circuit, PWM can potentially solve all the challenges of the microLED display driving.

But... such circuits are *much more complex*: more transistors + in-pixel memory and *require very high quality transistor performance*.

Therefore...

TFT not sufficient?

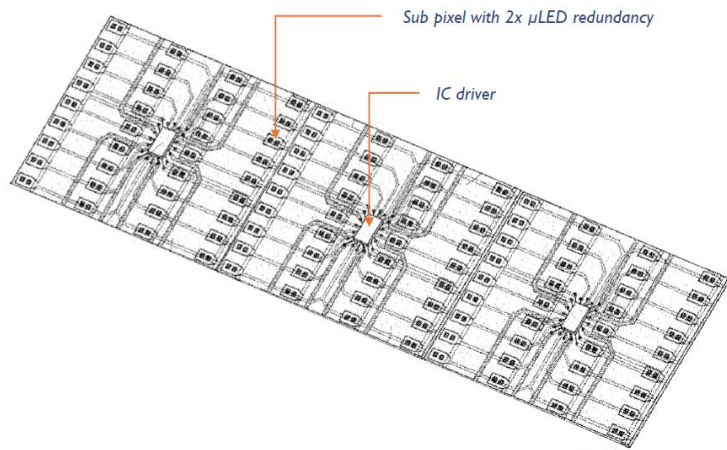
→ CMOS technology

# CHALLENGES IN THE LED DISPLAY DRIVING

## microLED CMOS driving: Existing solutions

### Micro ICs transferred on the substrate:

LuxVue



A  $\mu$ LED display where discrete ICs positioned on the front face drive groups of 36 subpixels featuring a 2x redundancy. (Source: LuxVue patent US 9,318,475)

Source: Yole

X-Celeprint

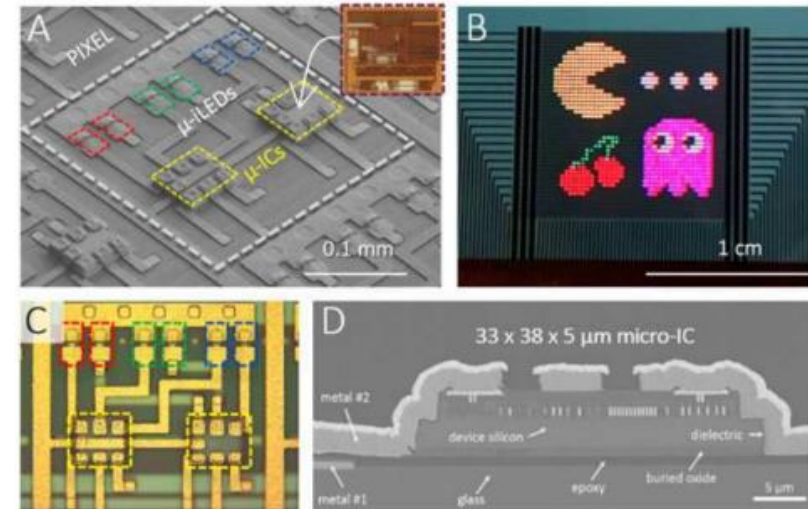


FIGURE 23 — Active-matrix microscopic inorganic light-emitting diode display on a glass substrate. The left micrographs (A, C) show a pixel with redundant control and emitters. Each controller separately controls a group of three microscopic inorganic light-emitting diodes ( $\mu$ LEDs) (each pair of  $\mu$ LEDs of a common color are adjacent). The upper right photograph (B) shows the entire uncompensated operational display and (D) is a cross section of the controller.

C. Bower et al., “Emissive displays with transfer-printed assemblies of  $8 \mu\text{m} \times 15 \mu\text{m}$  inorganic light-emitting diodes”, *Photonics Research*, Vol. 5, N°2, pp A23-29 (2017)

# CHALLENGES IN THE LED DISPLAY DRIVING

## microLED CMOS driving: Existing solutions

SONY Cledis

### Micro ICs transferred on the *tile*:

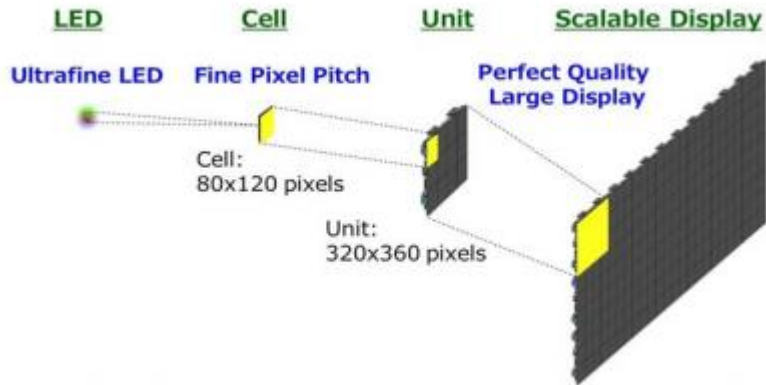
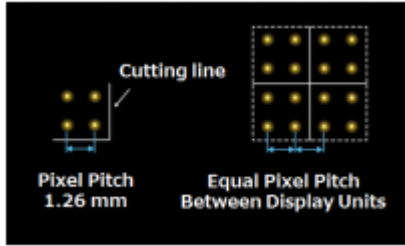


Figure 3. Structure of the Crystal LED display system.



Figure 2. Crystal LED display system commercialized as a scalable display system.

“Technologies for the Crystal LED Display System”,  
Goshi Biwa et al.; Display Week San Jose 2019

“RGB micro LEDs and microscale IC (micro IC) have been placed in each pixel and integrated into the active matrix system”

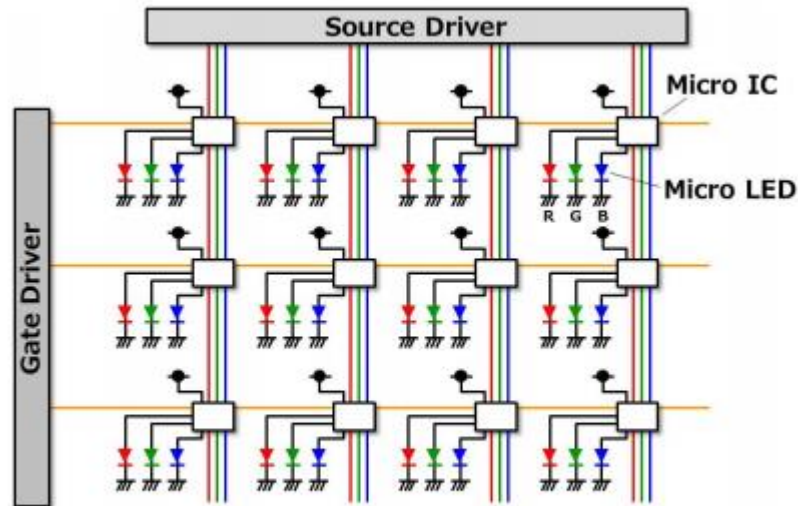


Figure 8. Example of active matrix driving using RGB micro LEDs and the micro IC in each pixel.

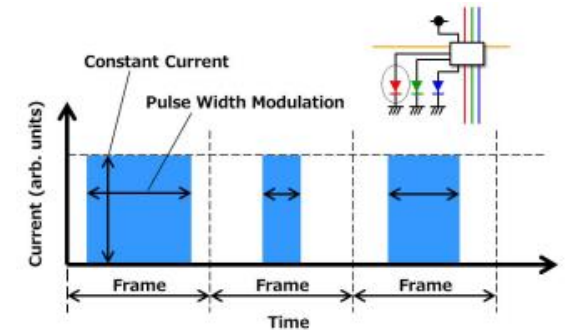
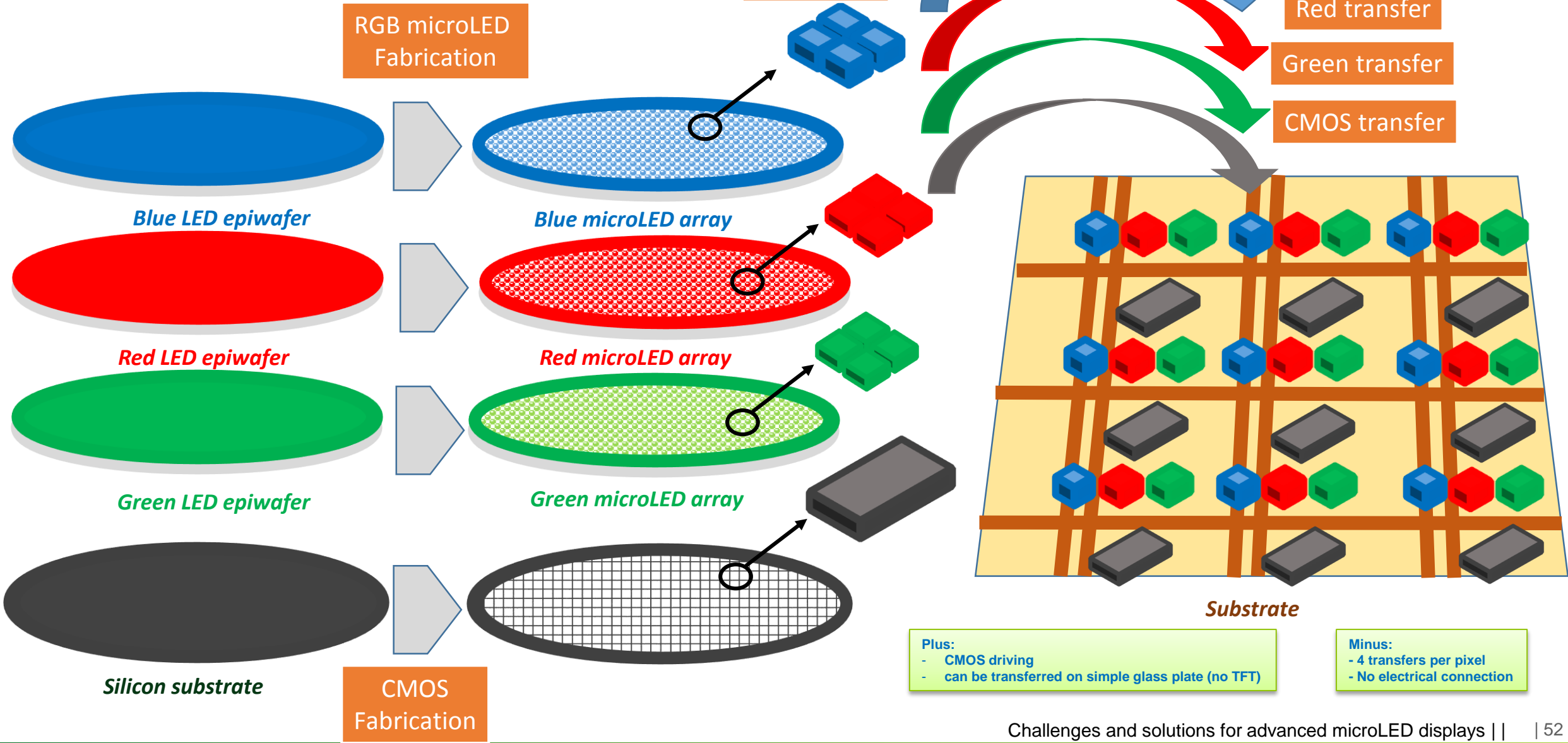


Figure 9. Example of constant current pulse width modulation of the micro LED by the micro IC.

“Integrating these novel active matrix driving and video processing controls such as dithering has achieved superior linearity even below 0.01 up to 1000 cd/m<sup>2</sup>”

# CHALLENGES IN THE LED DISPLAY DRIVING

Micro ICs transferred on the substrate:



- Driving microLED displays: a new solution

# CHALLENGES IN THE LED DISPLAY DRIVING

New LETI solution:

New concept:

Driving circuit is *embedded* with the microLED

The transferred unit includes: RGB microLEDs *and* the CMOS driving circuit

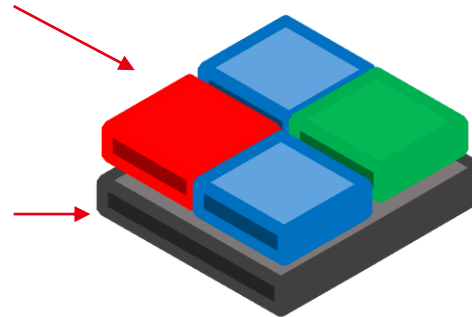
How?

1- Elementary unit:

All-in-one RGB LEDs *on* CMOS

RGB microLEDs

Driving circuit



2- Transfer of Elementary unit:

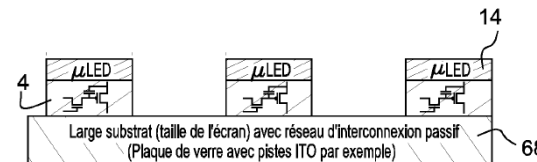


Fig. 6I

(10) Numéro de publication internationale  
WO 2017/089676 A1

- Fabricating high performance microLED displays

# CHALLENGES IN THE LED DISPLAY DRIVING

**New solution:**



Blue LED epiwafer



Red LED epiwafer

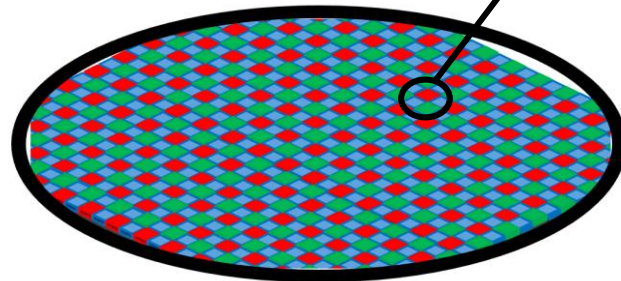
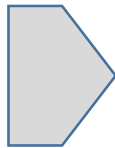


Green LED epiwafer



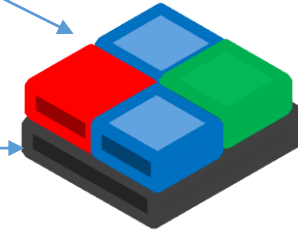
Silicon wafer

Wafer scale RGB microLED on CMOS integration



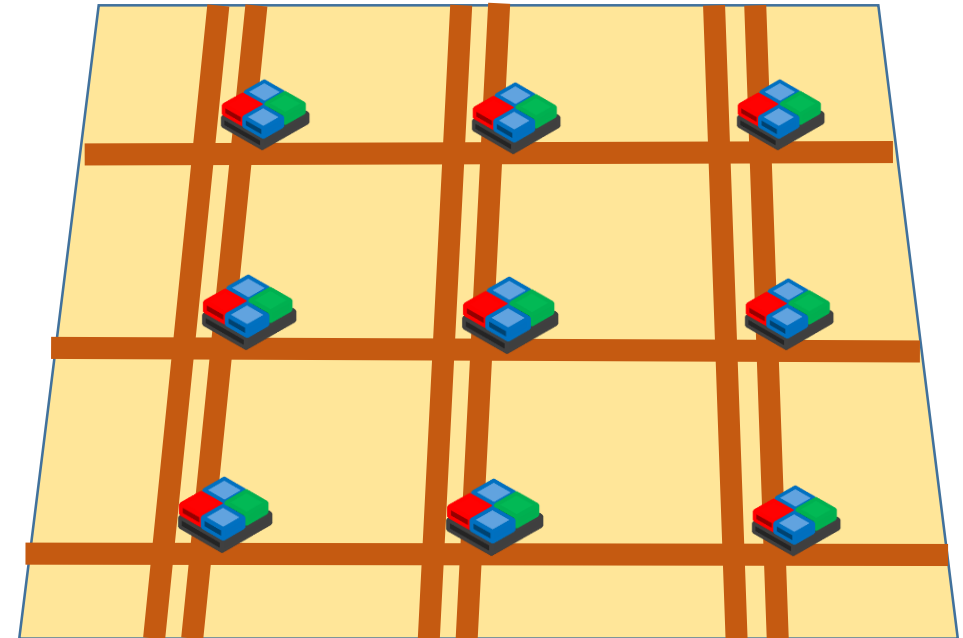
RGB microLEDs

Driving circuit



Transfer

Substrate



- Plus:**
- One transfer per pixel
  - CMOS driving
  - Many other features (see next)
- Minus:**
- ?

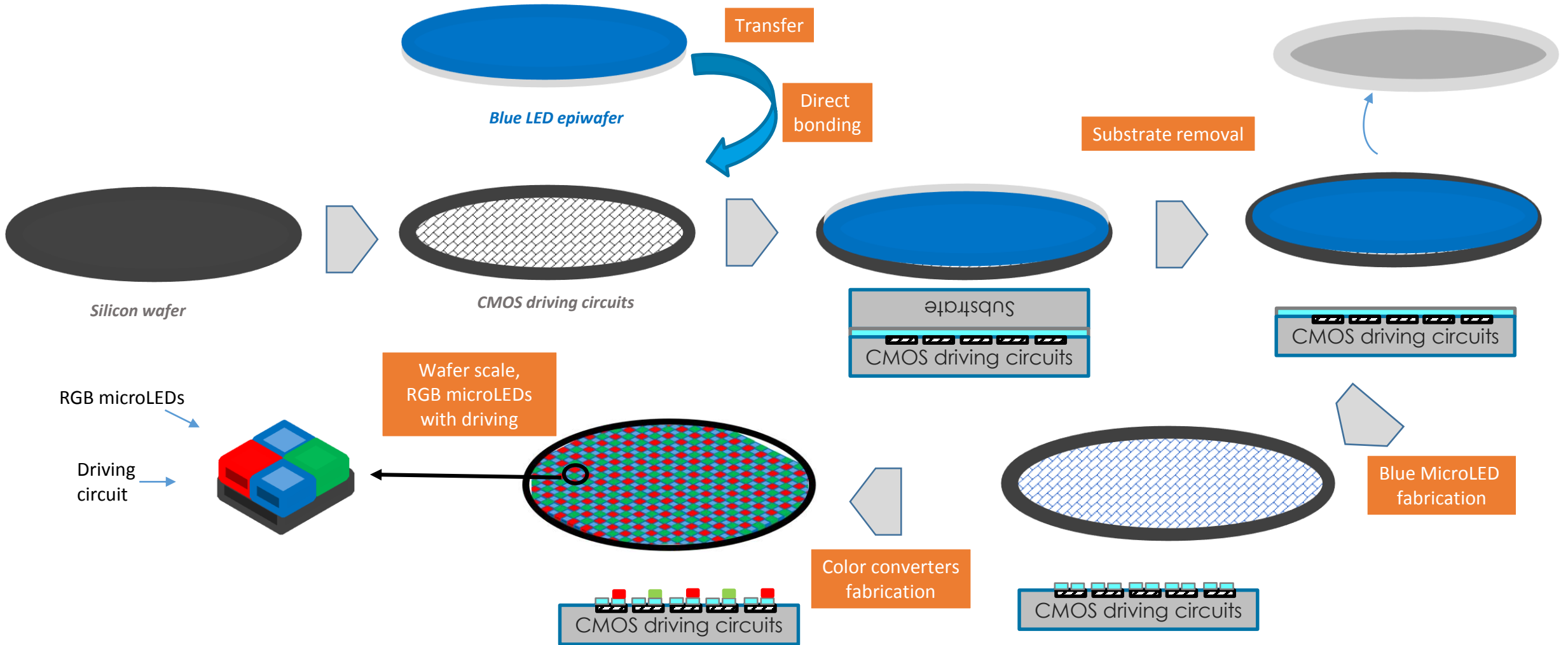
- Receiving substrate:**
- Need only lines /columns



# CHALLENGES IN THE LED DISPLAY DRIVING

LETI solution

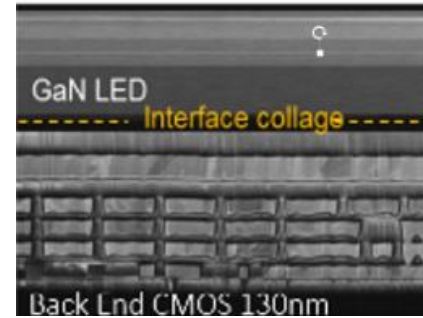
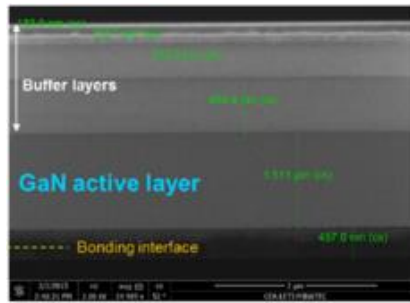
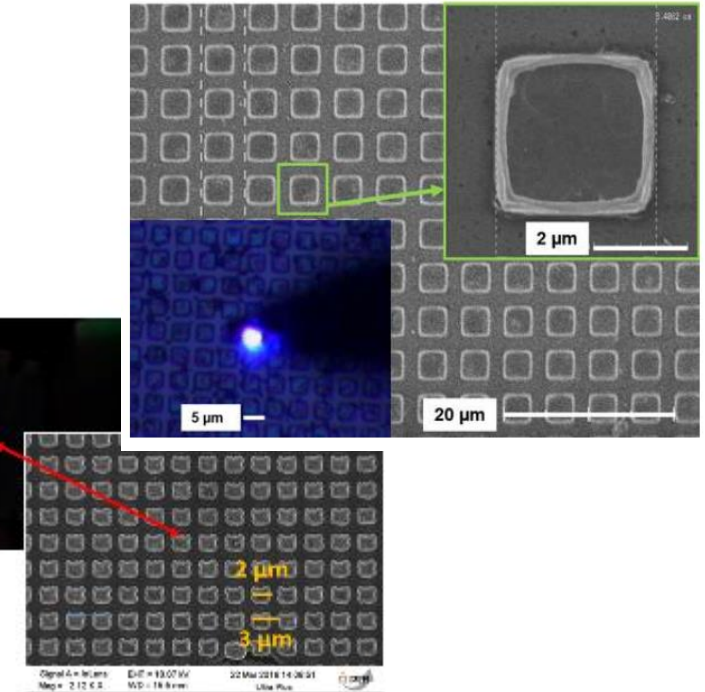
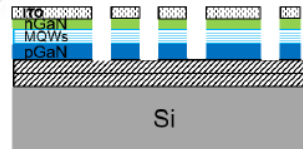
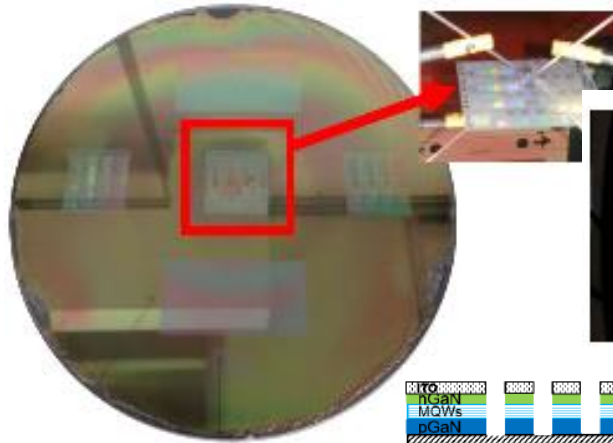
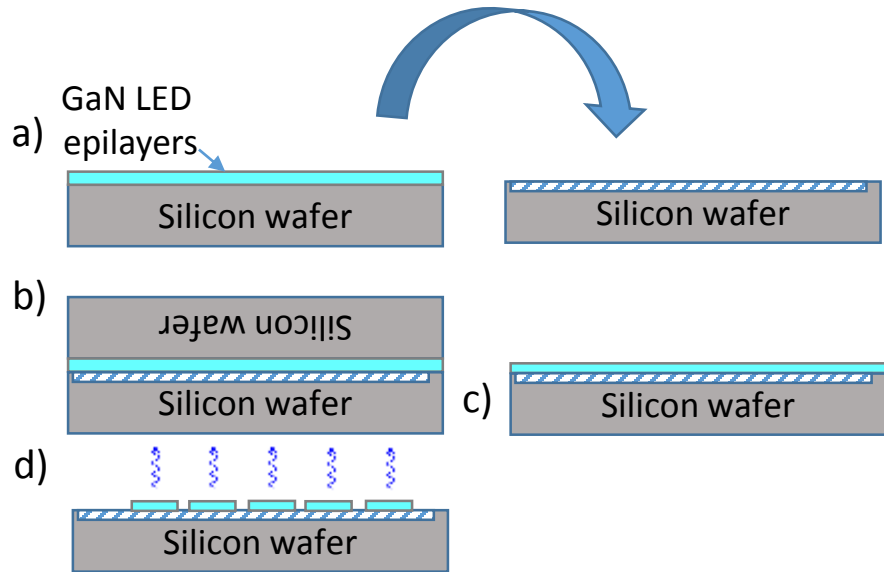
Wafer-scale, RGB microLED-on-CMOS integration



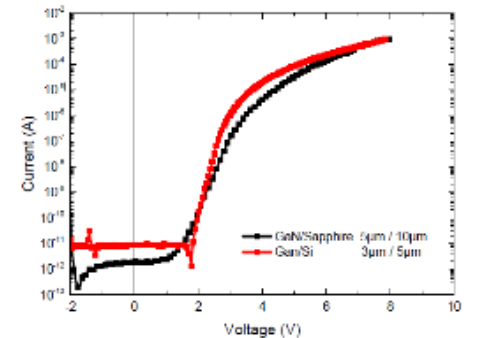
# CHALLENGES IN THE LED DISPLAY DRIVING

Wafer-scale, RGB microLED-on-CMOS integration

## Proof-of-concept



Display Week 2017



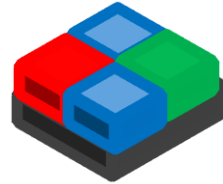
Proof-of-concept for fabricating full CMOS microLED units

- Advantages of the new solution

# CHALLENGES IN THE LED DISPLAY DRIVING

## ADVANTAGES OF THE NEW SOLUTION

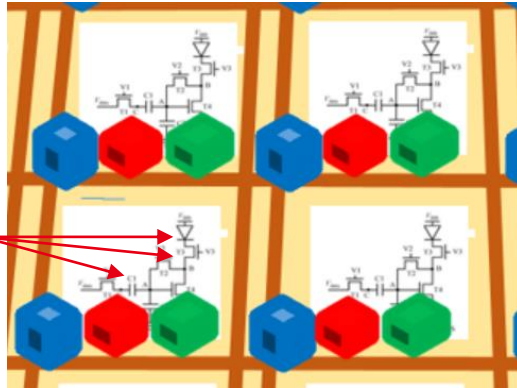
MicroLED are directly stacked onto the circuit:



→ Shortest connection (fast, PWM)

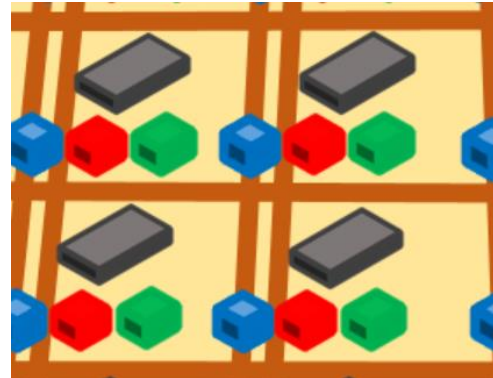
→ Best fill ratio

μLED + TFT

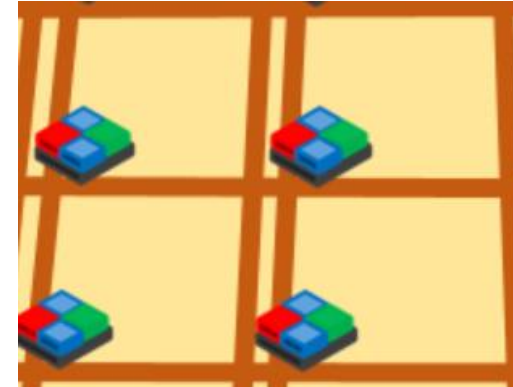


TFTs

μLED + CMOS



μLED on CMOS



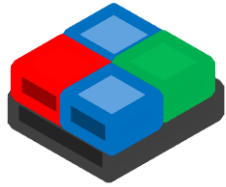
Biggest transparent area → Transparent displays

Less reflective part (contrast) → Ultra-high contrast displays

# CHALLENGES IN THE LED DISPLAY DRIVING

## ADVANTAGES OF THE NEW SOLUTION

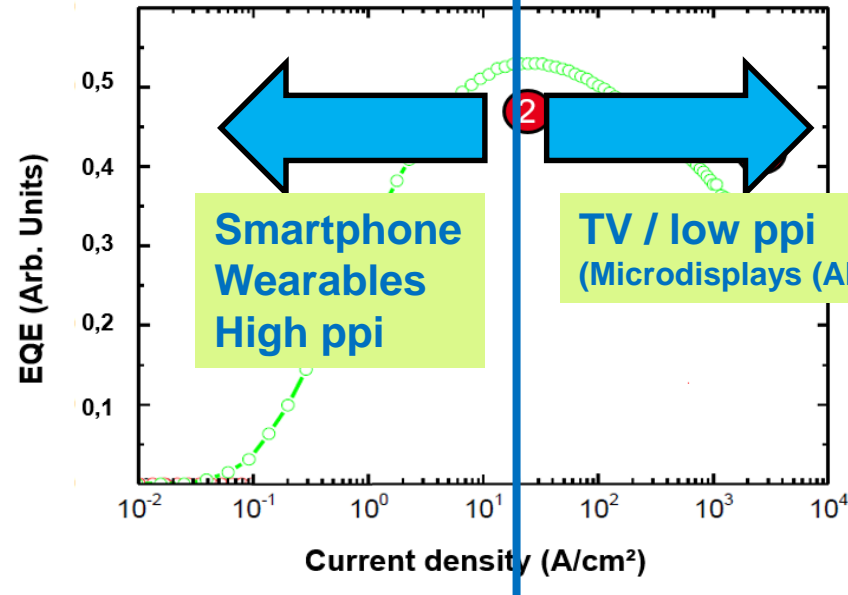
### Performance....



MicroLED for Direct view displays: Emitting surface  $\neq$  pixel area      Nits? at what level?

500 – 1000 nits (Display) →

*Nits at  $\mu$ LED level strongly depend on application  
Same for current density....*



### Advantage of CMOS:

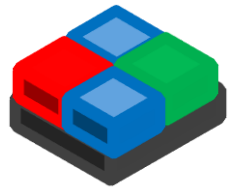
Make complex circuit (PWM...) compact

Make performant circuit: IGZO limited to 15 cm<sup>2</sup>/V.s  
High mobility + short distance : less signal (pulse) distortion  
→ Image quality

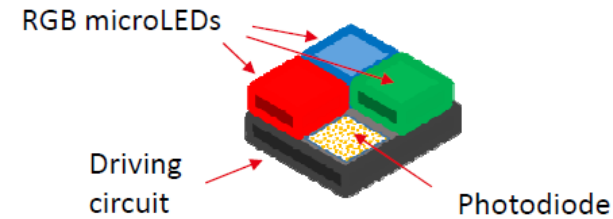
# CHALLENGES IN THE LED DISPLAY DRIVING

## ADVANTAGES OF THE NEW SOLUTION

### Additional functions:



The elementary unit can embed sensing, actuating,...



All CMOS compatible

- Haptics on display
- Sound on display
- ....

### Display yield and testing:

Necessary to identify "Known Good Dies" after microLEDs after fabrication

Wafer level fabrication → Embedded, contactless testing possible

### Mass transfer technology:

- 1 transfer instead of 3 or 4
- Transfer technology-agnostic,
- CMOS: possible to fabricate anchors, tethers.

# CHALLENGES IN THE LED DISPLAY DRIVING

## ADVANTAGES OF THE NEW SOLUTION

### New receiving substrate:

A simple substrate with only columns and lines

- **Low cost:** non-lithographic techniques: ink-jet, stencil printing, ...  
→ lower investment level required to enter the display market
  
- **No size limit:** Today TFT at GEN10.5, ok for 65/75-in. TVs. Not for 100-in. or bigger TVs.  
With the simple substrate, no size limit.  
→ A can be a game changer for microLED displays?
  
- **Freedom of material:** : glass, plastic, metal; rigid flexible, ...  
→ New applications...

## ***Conclusion for microLED for large area displays***

**Strong challenge for transfer process, connections:  
→ Microtube technology suitable**

**Strong challenge for driving microLED displays:**

**New solution: all-in-one RGB-on-CMOS unit:**

- helps solutioning driving**
- many more features: applications, fonctionnalités,...**

**Next steps: full integration....**



***Thank you for your attention!***